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Vertical GaN Power Electronics – Opportunities and Challenges

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VEHICLE TECHNOLOGIES OFFICE



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- **Overview of WBG Power Electronics**
- **Medium-Voltage Vertical GaN Devices**
 - **PN Diodes**
- **Vertical GaN Devices for Electric Vehicles**
 - **JBS Diodes and MOSFETs**

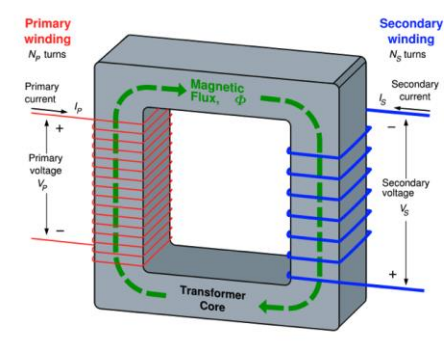
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What Are Power Electronics?

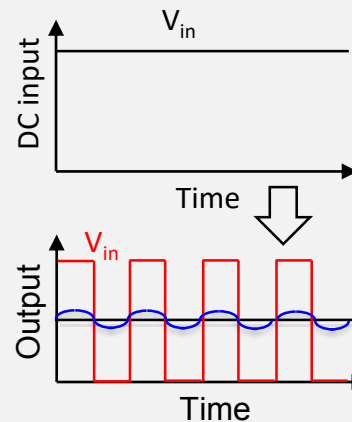
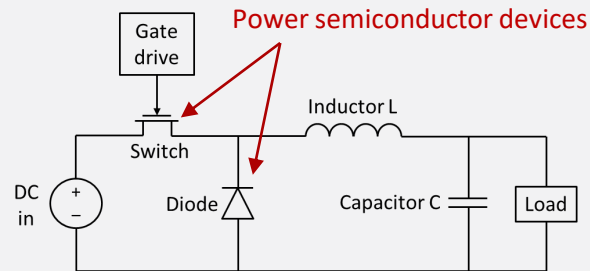


Power electronics: Application of solid-state electronics for routing, control, and conversion of electrical power

Passive transformers (dumb)

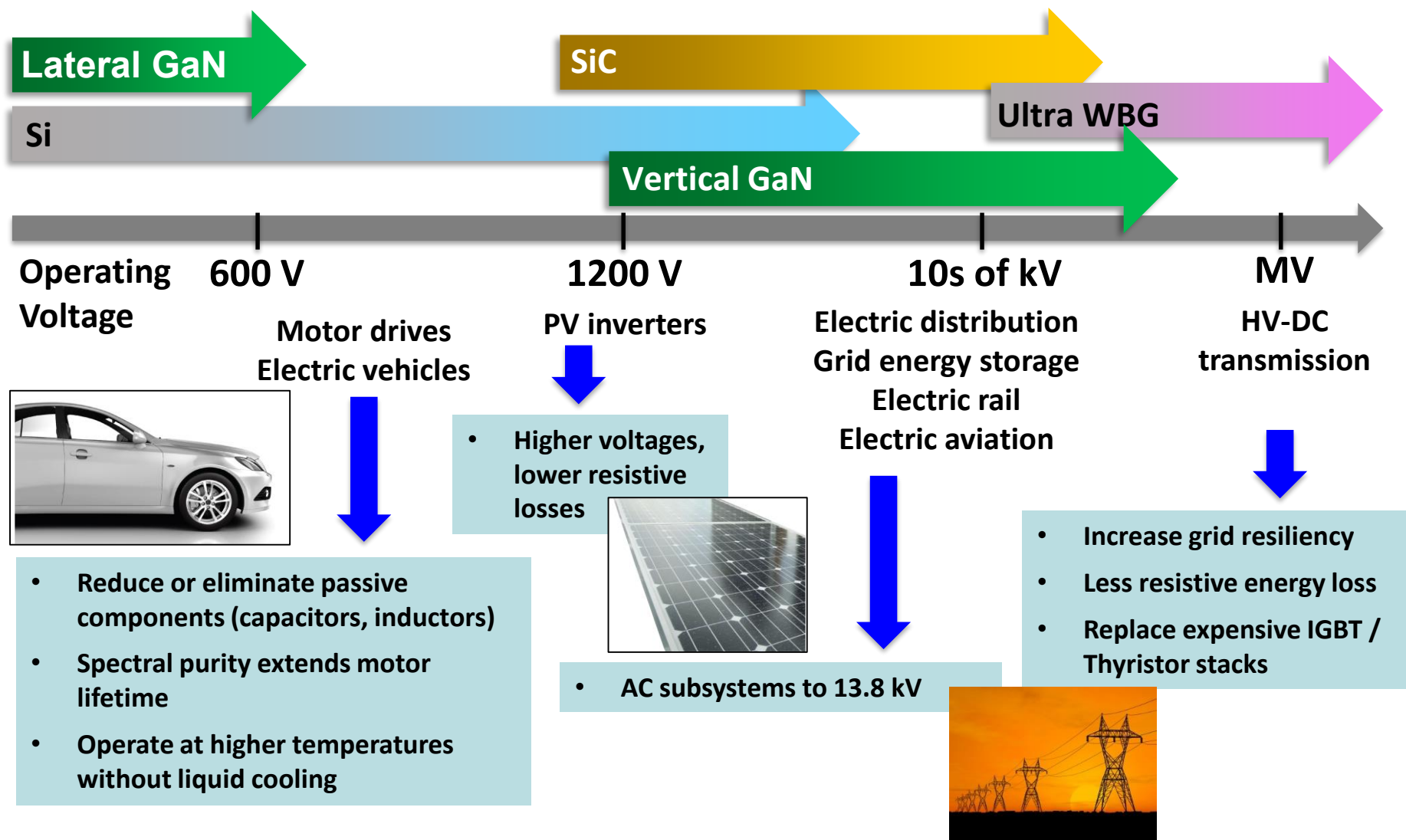


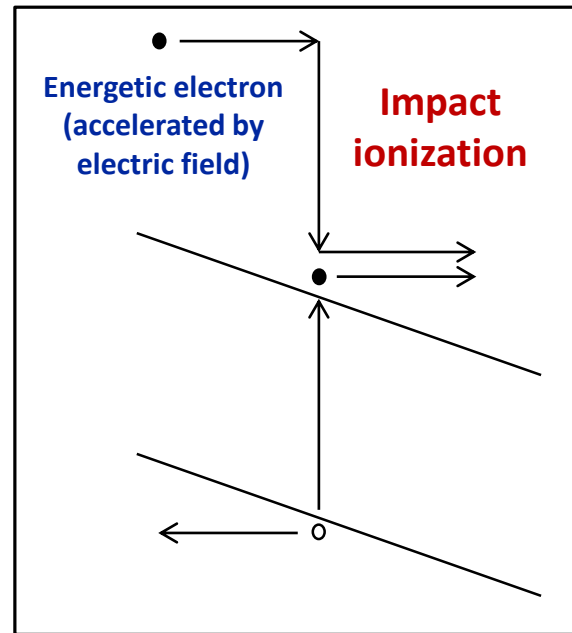
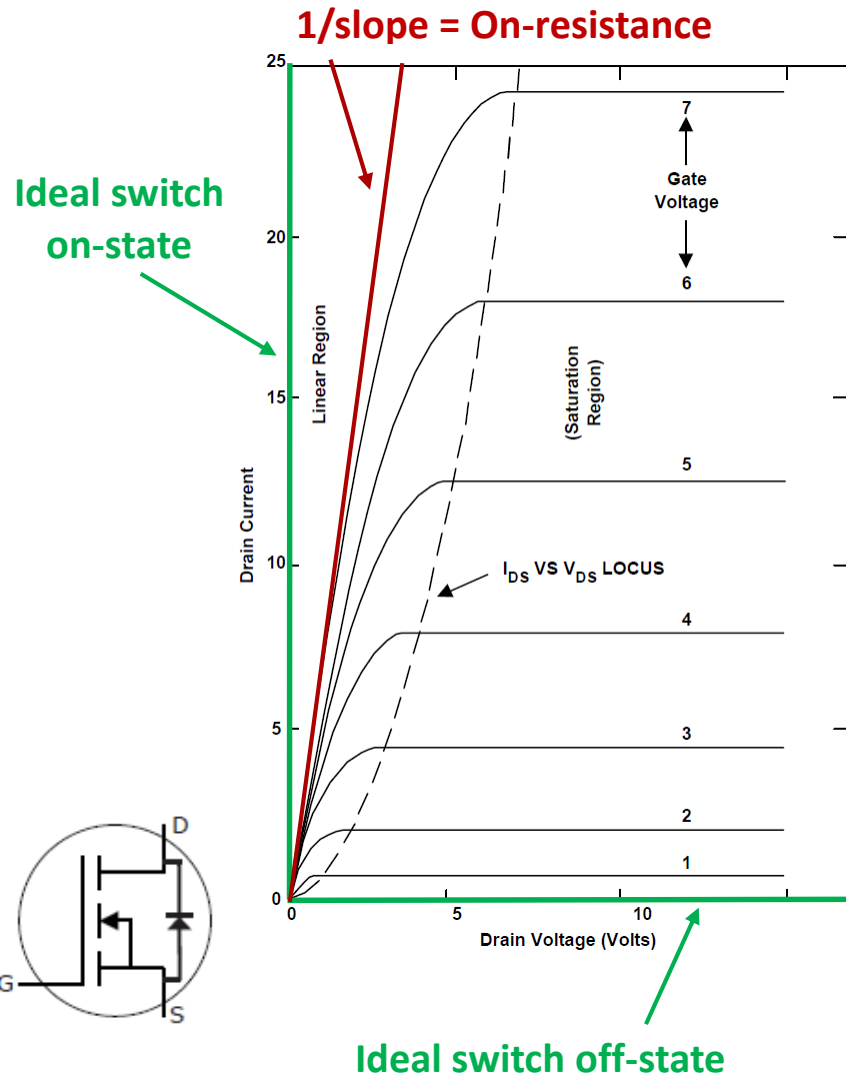
Power Electronics – active switching (smart)



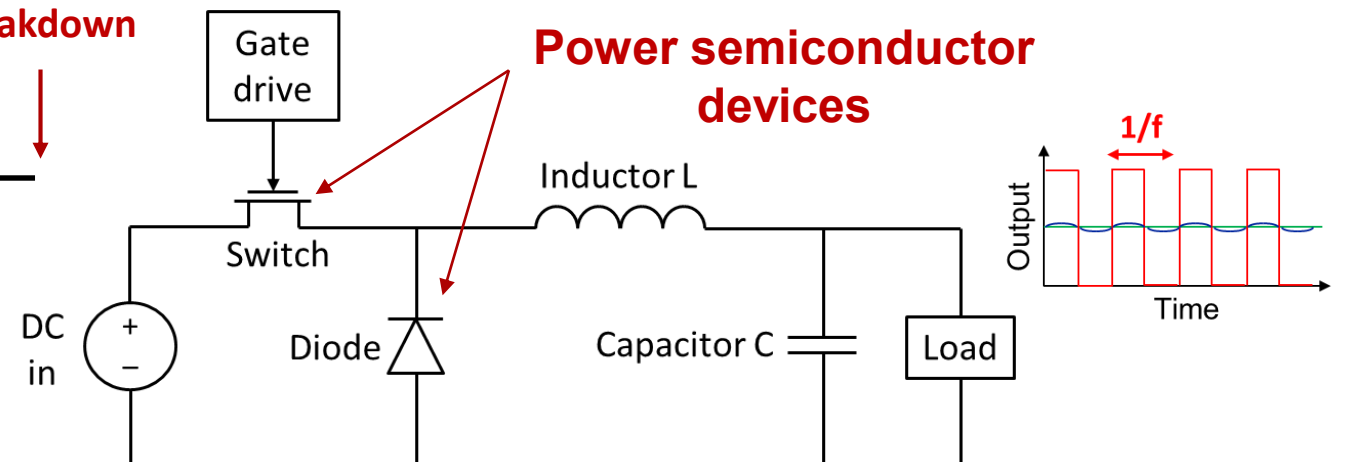
- Current power electronics are limited by the properties of Silicon semiconductor devices
- New system capabilities are enabled by:
 - Higher switching frequency (enables better SWaP)
 - Lower power loss
 - Higher temperature operation
- **Motivation for WBG/UWBG semiconductors**

Power Electronics for Energy Efficiency



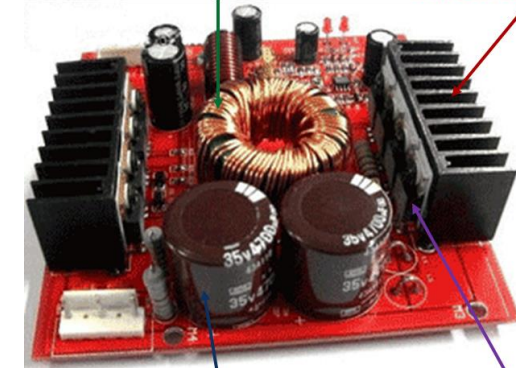


Avalanche breakdown



Magnetics

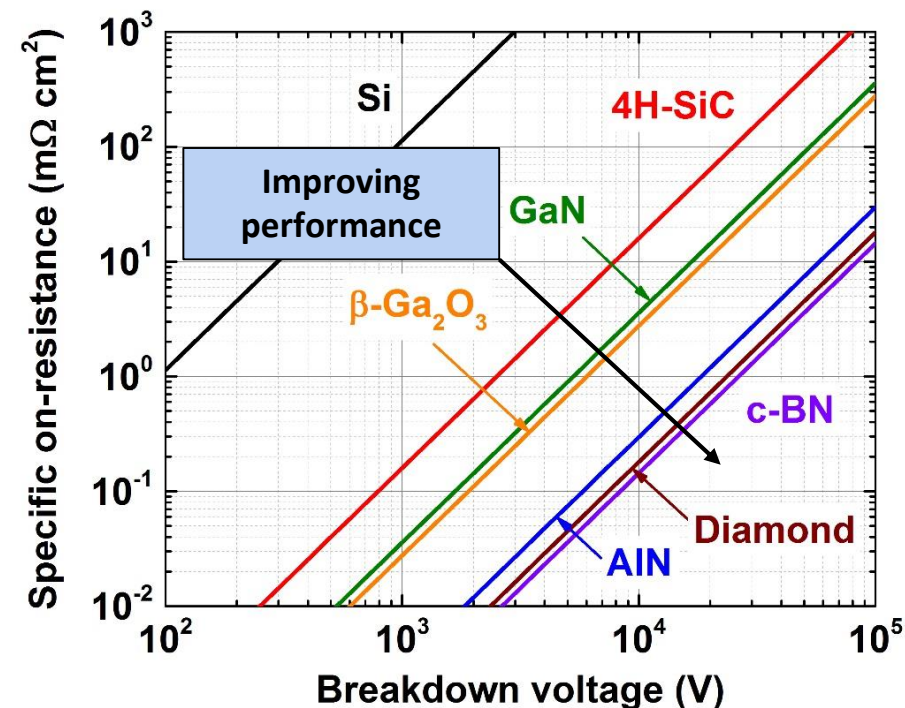
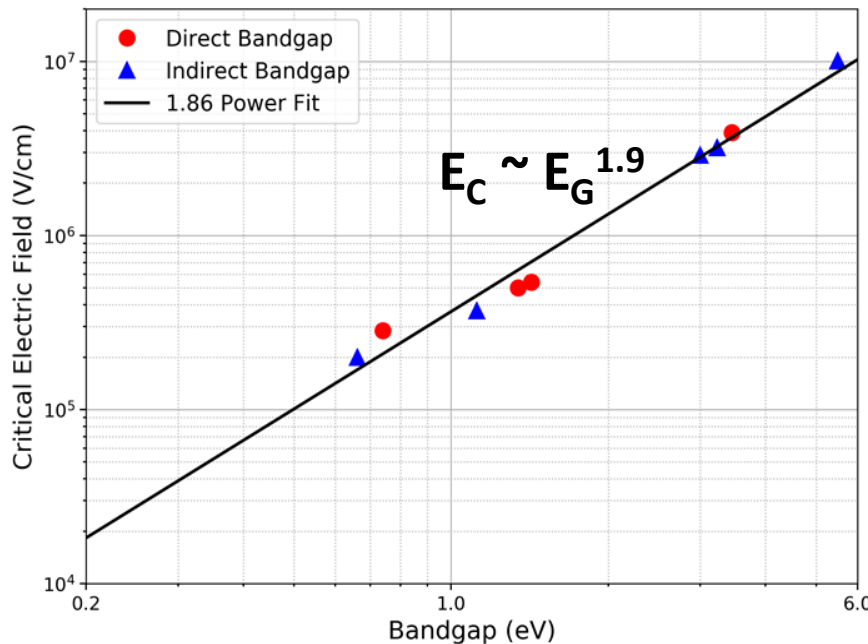
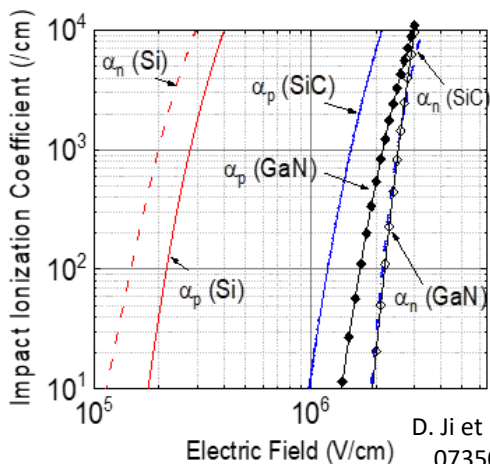
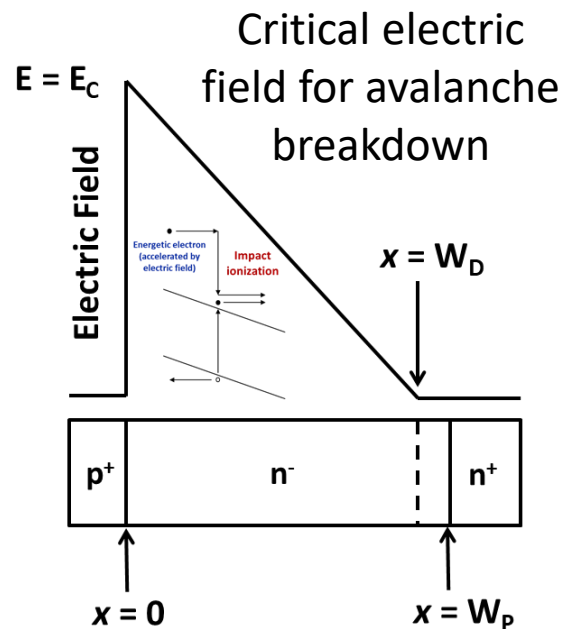
Thermal management



Capacitors

Semiconductor switches

Advantages of WBG/UWBG Semiconductors



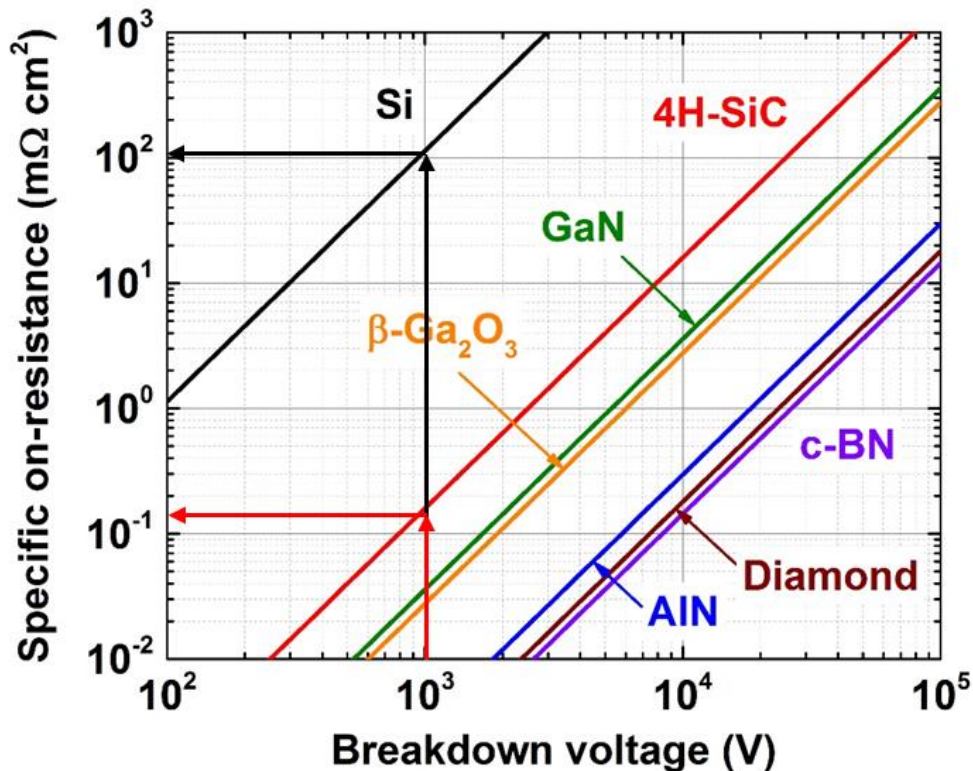
Vertical device:

$$UFOM = V_B^2 / R_{on,sp} = \epsilon \mu_n E_C^3 / 4$$

Lateral device:

$$LFOM = V_B^2 / R_{on,sp} = q \mu_{ch} n_s E_C^2$$

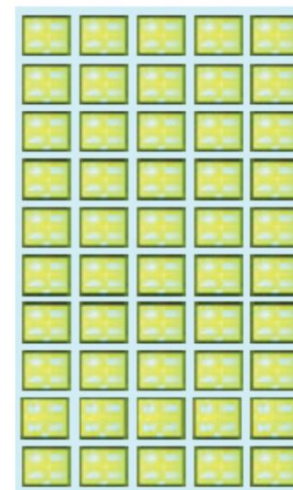
Scaling of WBG/UWBG Power Devices



The scaling that results from the properties of WBG and UWBG materials can be utilized to optimize for switching frequency, conduction loss, and switching loss

- For equivalent breakdown voltage, get lower $R_{on}A$ for (U)WBG device
- For same R_{on} , (U)WBG device can have *smaller area*
 - Smaller area results in *less capacitance*
 - Gives a *faster switching transient* and *lower loss per switching cycle*

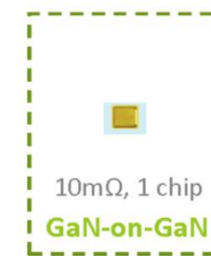
For a given on-resistance (R_{on}) of 10mΩ:



500mΩ, 50 chips
Si-MOSFET

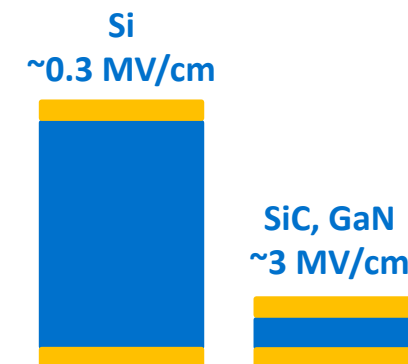


40mΩ, 4 chips
GaN-on-Si
SiC



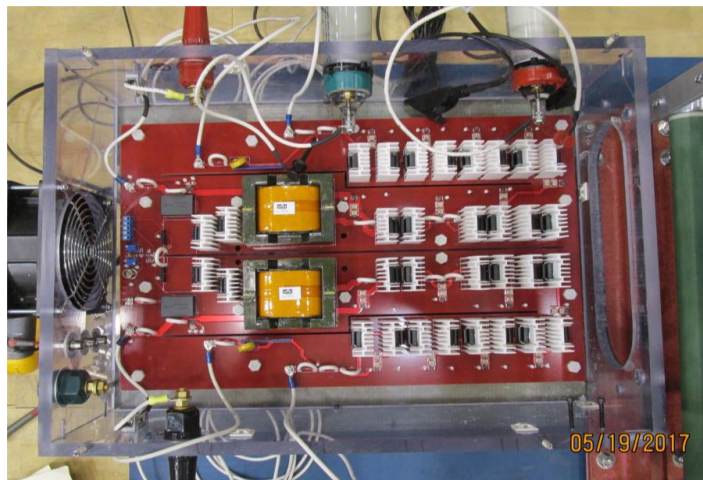
10mΩ, 1 chip
GaN-on-GaN

GaN-on-GaN lowers die cost while improving $R_{on} \times C_{off}$ switching characteristic



Thinner drift layers required for increasing E_c

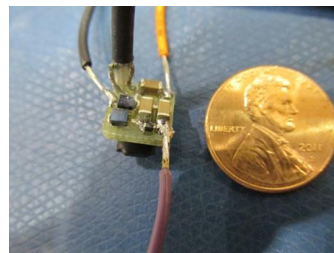
Improvements in Converter Power Density



SNL SiC hybrid switched-capacitor boost converter (ARPA-E)

- First prototype: 0.5 kV \rightarrow 10.1 kV (gain = 16.8) at 2.6 kW, 95.3% efficient, 410 in³
- Second prototype: +2% efficiency, 55% volume

Over an order of magnitude improvement in power density is enabled by WBG and UWBG semiconductors compared to Si

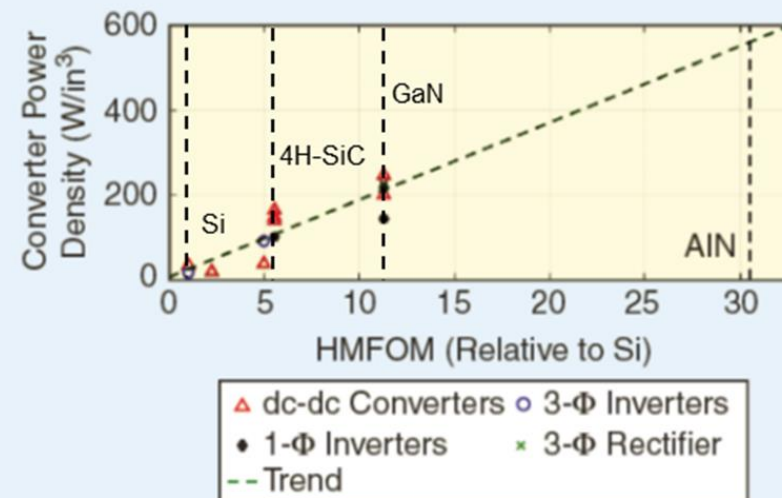


SNL GaN HEMT "Coin Converter"
90 V, 90 mA \rightarrow 215 W/in³

SNL GaN HEMT microinverter
400 W in 2.4 in³ \rightarrow 167 W/in³



SOA commercial microinverter
250 W in 59 in³ \rightarrow 4.2 W/in³



R. J. Kaplar, J. C. Neely, et al., *IEEE Power Electronics Magazine* (March 2017)

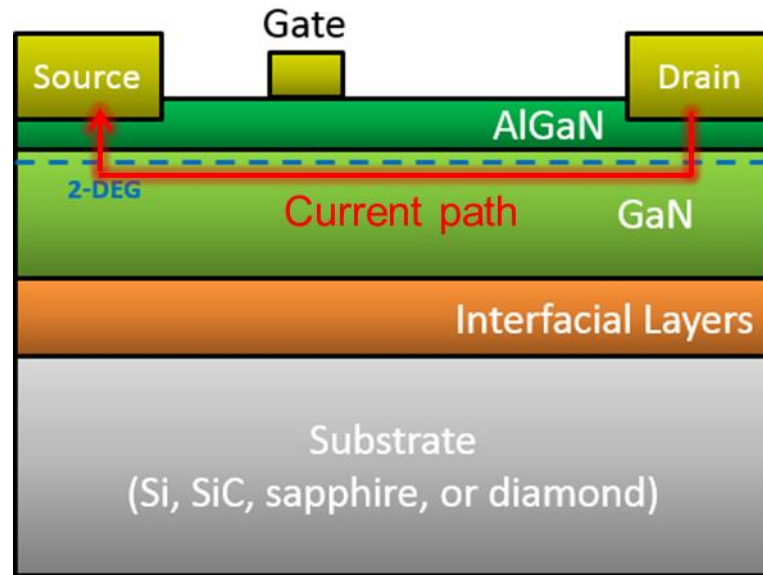
Relative Figures of Merit:

- Vertical UFOM = $\epsilon \mu_n E_C^3$
- Lateral LFOM = $q \mu_{ch} n_s E_C^2$
- Huang Material FOM = $E_C \mu_n^{1/2}$
- *HM-FOM seems to be a good predictor of power density in a variety of power converter types*

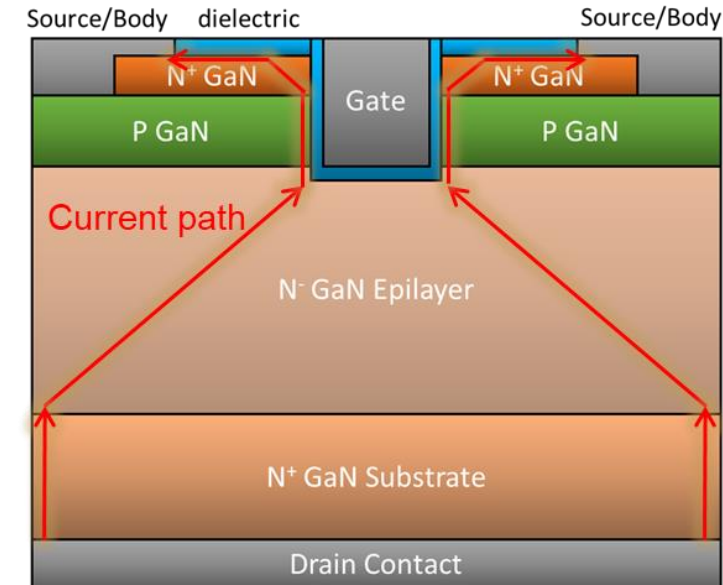
Lateral vs. Vertical GaN Power Devices



**Lateral Current Flow
(HEMT)**



**Vertical Current Flow
(Trench MOSFET)**

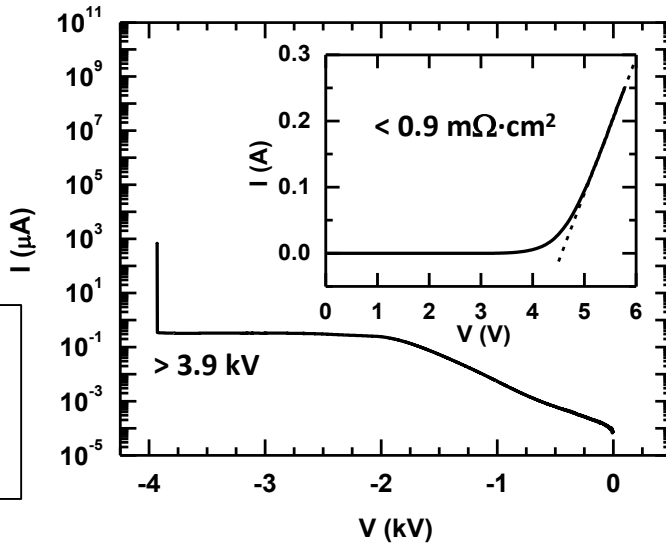
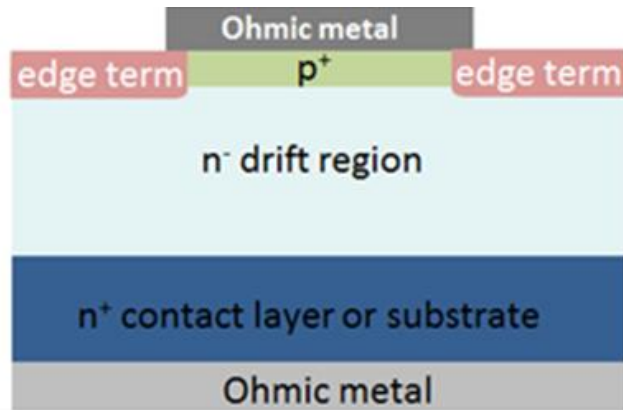


- Polarization-doped heterostructure
- High electron mobility in 2DEG for low R_{ON}
- High-frequency operation (up to ~ 1 MHz)
- Low blocking voltage ($< \sim 650$ V, scales with area)
- Typically grown on foreign substrate
- Commercially available

- Selective-area impurity doping required
- Mobility limited by channel
- Capable of large blocking voltages (> 1200 V, not dependent on area)
- Grown on native GaN substrates

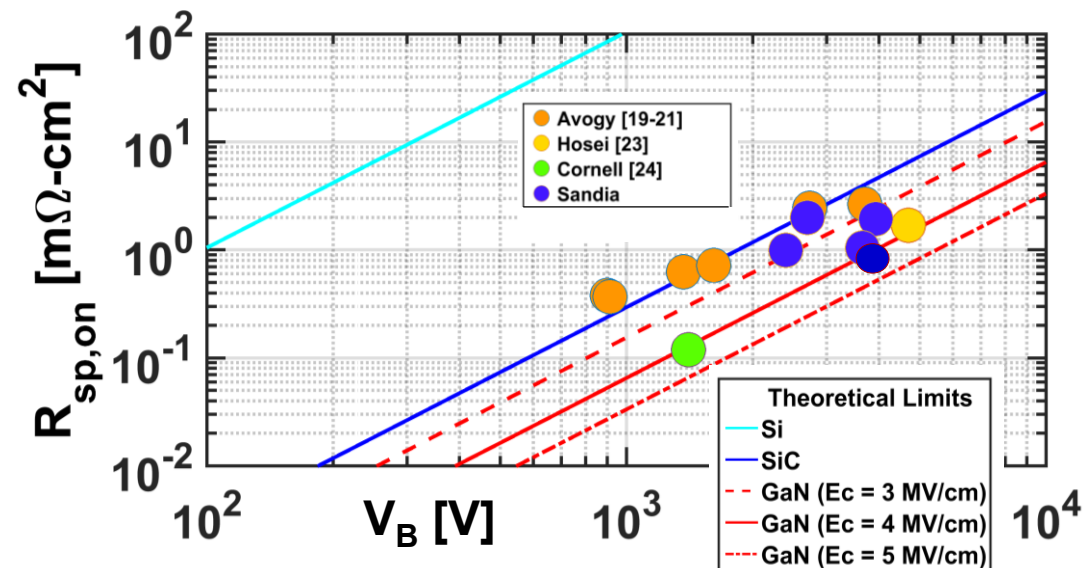
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Overview of Vertical GaN Technology



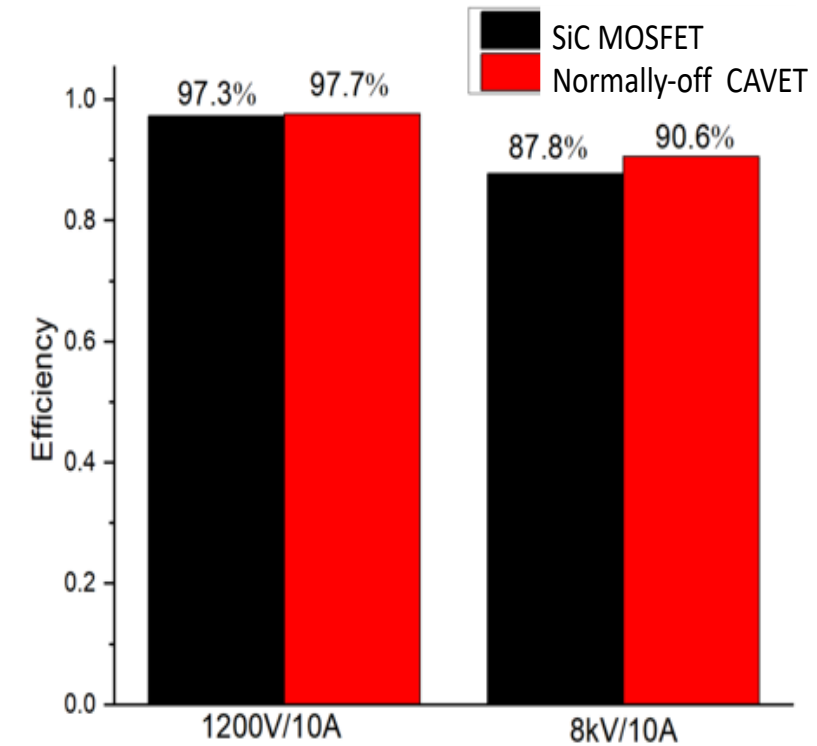
A. Armstrong et al., Elec. Lett. 52(13), 1170 (2016)

- Need to extend the limits of vertical GaN power device technology for medium-voltage applications (~1.2-20 kV)
 - Need to increase V_B by 4x from today's SOA
 - Challenges: Thick drift region, low net doping, edge termination
- Need to establish a domestic foundry process for vertical GaN power devices



Vertical GaN Advantages for MV Power Electronics

- Critical field of GaN ~ 2.8 MV/cm at $N_D = 1 \times 10^{16} \text{ cm}^{-3}$ and room temperature based on most recent impact ionization measurements [1]
- Slightly higher than E_c of SiC at the same temperature and doping [2]
- But higher mobility of GaN $\sim 1200 \text{ cm}^2/\text{Vs}$ [3] compared to $\sim 950 \text{ cm}^2/\text{Vs}$ for SiC [2] at the same doping and temperature lead to improvements in power converter efficiency [4], **particularly for medium-voltage devices ($> 1.2 \text{ kV}$)**
- But devices are not widely available – **a vertical GaN foundry is needed that monitors yield, reliability, etc.**



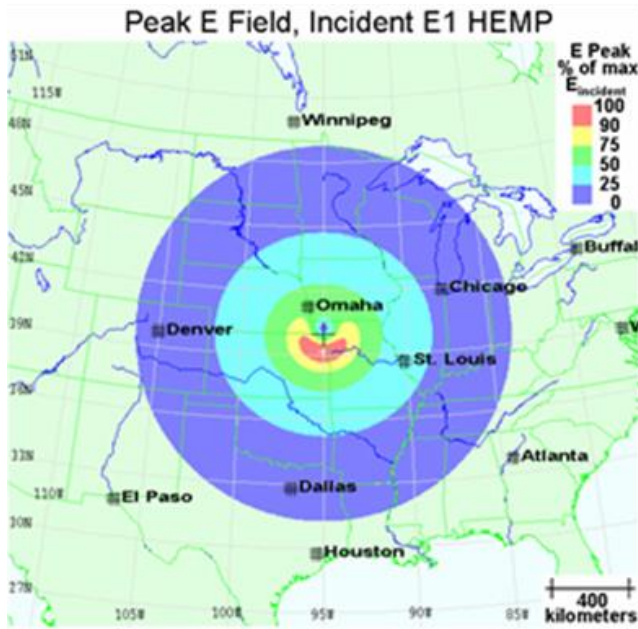
[1] D. Ji, B. Ercan, and S. Chowdhury, "Experimental Determination of Impact Ionization Coefficients of Electrons and Holes in Gallium Nitride Using Homojunction Structures," *Appl. Phys. Lett.* **115**, 073503 (2019).

[2] J. A. Cooper and D. Morissette, "Performance Limits of Vertical Unipolar Power Devices in GaN and 4H-SiC," *Elec. Dev. Lett.* **41**, 892 (2020).

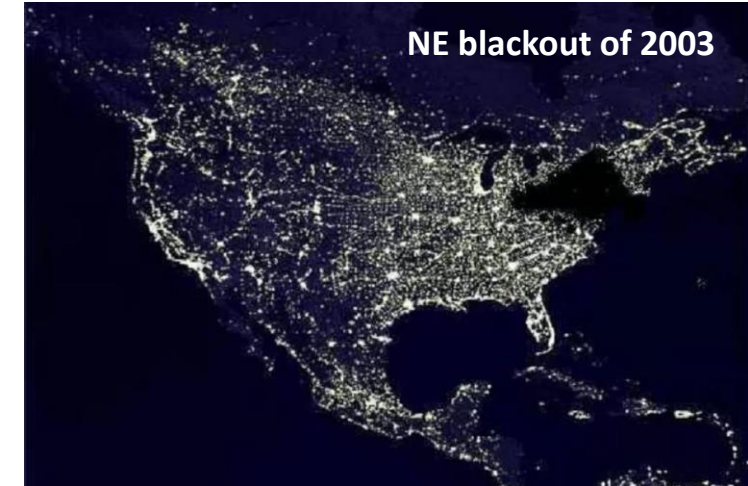
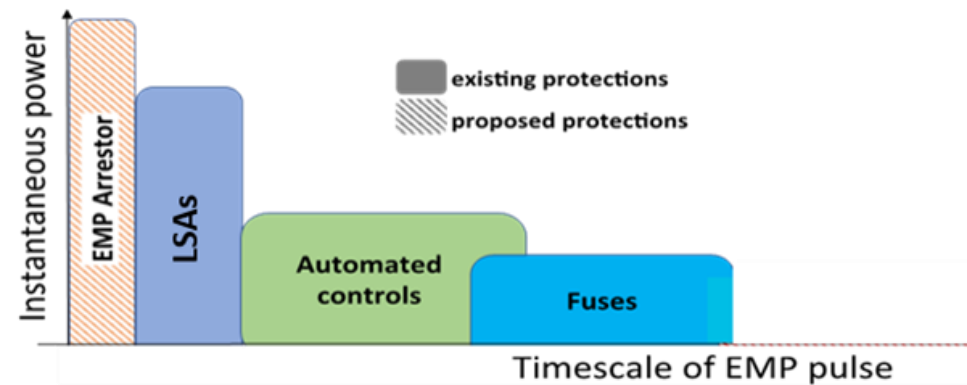
[3] I. C. Kizilyalli, A. P. Edwards, O. Aktas, T. Prunty, and D. Bour, "Vertical Power PN Diodes Based on Bulk GaN," *IEEE Trans. Elec. Dev.* 62(2), 414 (2015).

[4] D. Ji and S. Chowdhury, "On the Progress Made in GaN Vertical Device Technology – Special Issue on Wide Band Gap Semiconductor Electronics and Devices," *Int. J. High-Speed Elec. Sys.* **28(01n02)**, 1940010 (2019).

Fast Protection for the Electric Grid



- Electromagnetic pulses are a threat to the grid
 - Very fast E1 component ($< 1 \mu\text{s}$)
 - Unaddressed by current SoA technology (LSAs)

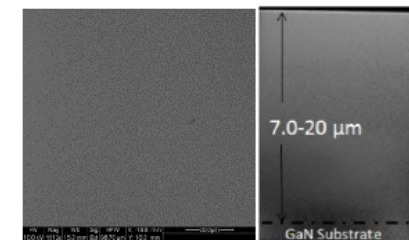
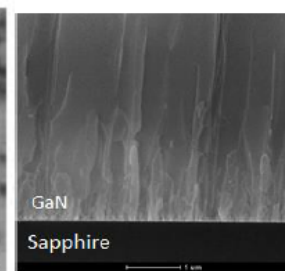
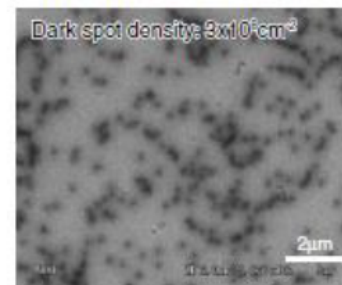
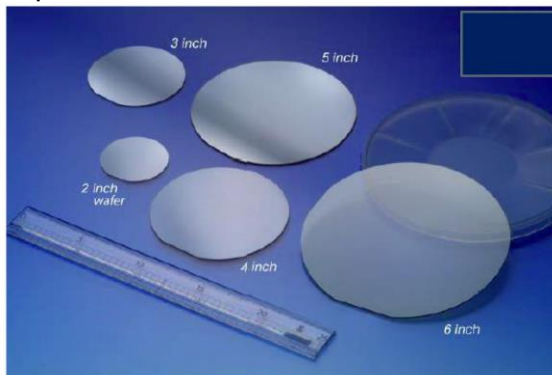


- Transient protection is needed for MV grid-connected systems

J. S. Foster Jr. et al., "Report of the Commission to Assess the Threat to the United States from Electromagnetic Pulse (EMP) Attack: Critical National Infrastructures," *Defense Technical Information Center* (2008).

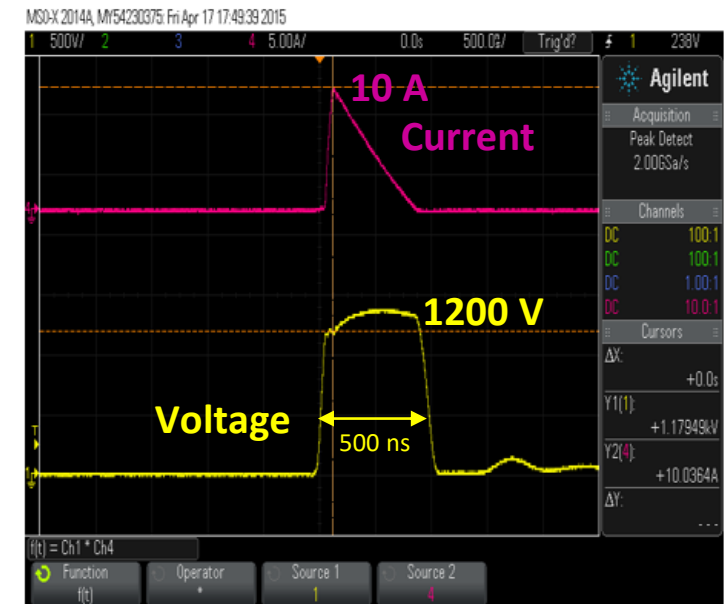
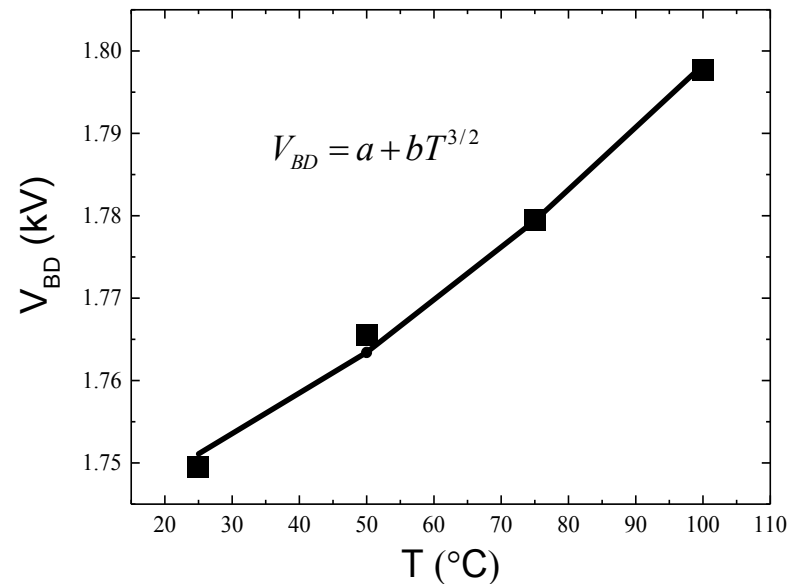
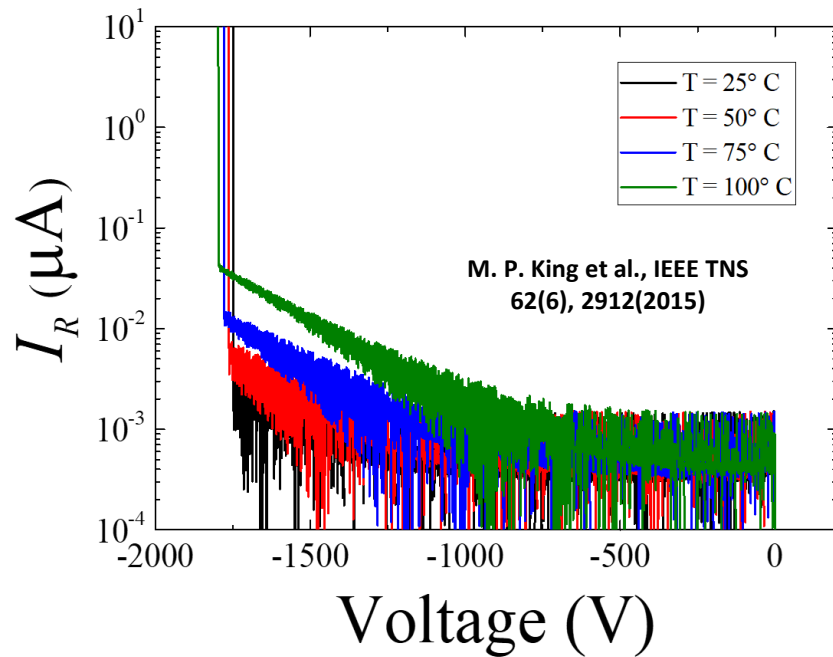
Native Substrates for Vertical GaN Devices

Attributes	GaN on Si	GaN on SiC	GaN on Bulk-GaN
Defect Density (cm⁻²)	10 ⁹	5x10 ⁸	10 ³ to 10 ⁶
Lattice Mismatch, %	17	3.5	0
CTE Mismatch, %	54	25	0
Layer Thickness (μm)	< 5	< 10	> 50
Breakdown Voltage (V)	< 1000	< 2000	> 5000
OFF State Leakage	High	High	Low
Device Types	Lateral	Lateral	Vertical and Lateral



Avalanche Ruggedness of Vertical GaN

- Avalanche breakdown mechanism demonstrated via temperature dependence
- Avalanche ruggedness demonstrated in real power switching circuits
- *Very different from the situation for GaN-on-Si power devices, where avalanche breakdown does not occur*

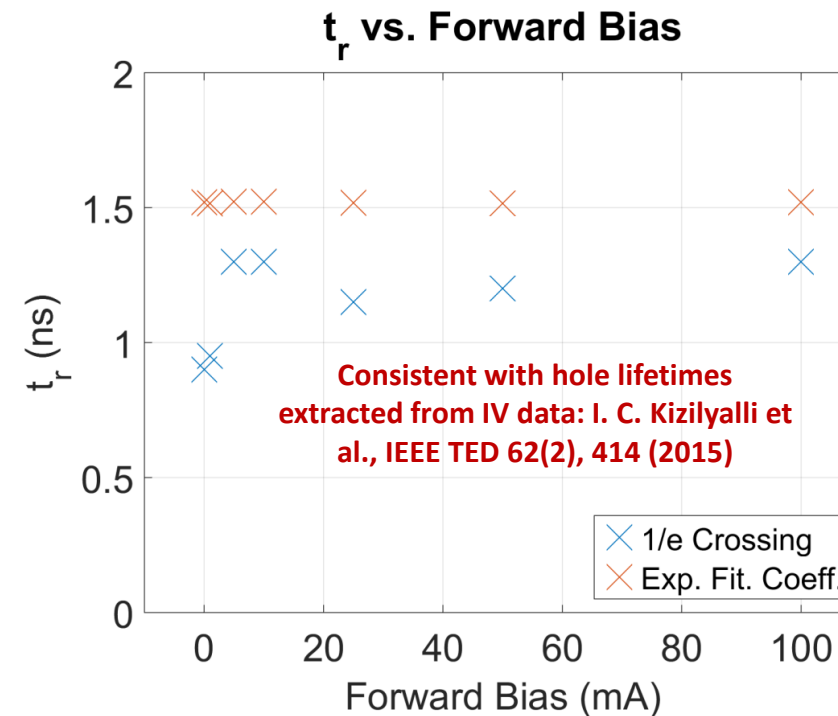
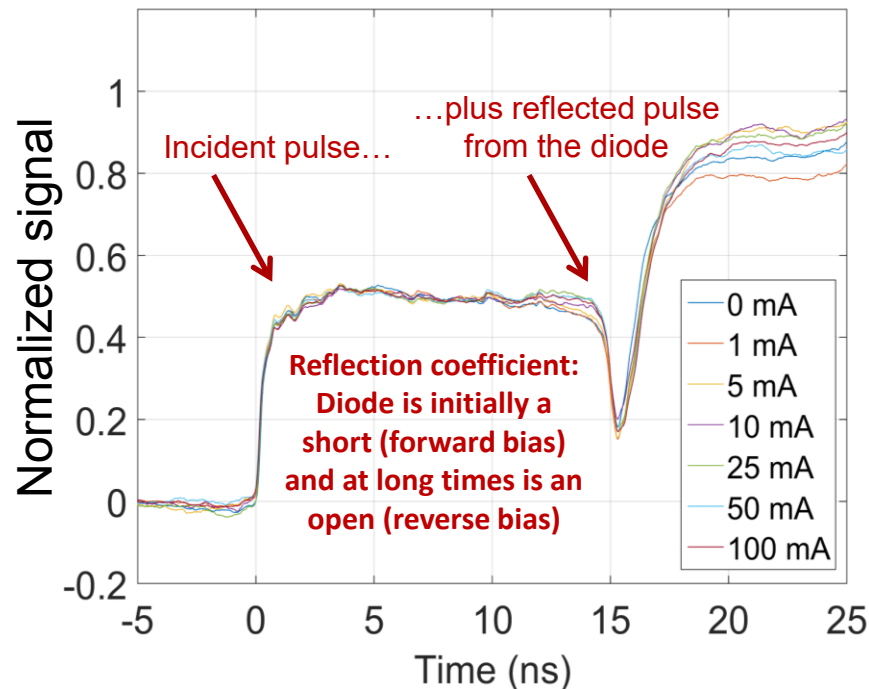


O. Aktas and I. C. Kizilyalli, IEEE EDL 36(9), 890 (2015)

Carrier Transport in Vertical GaN

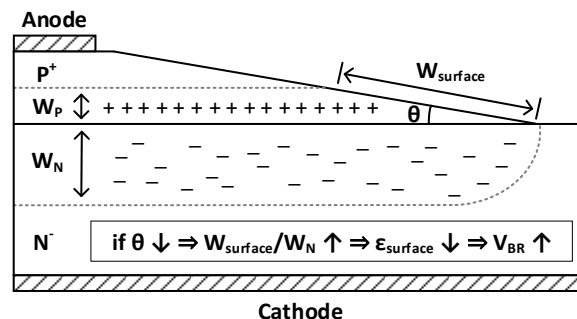
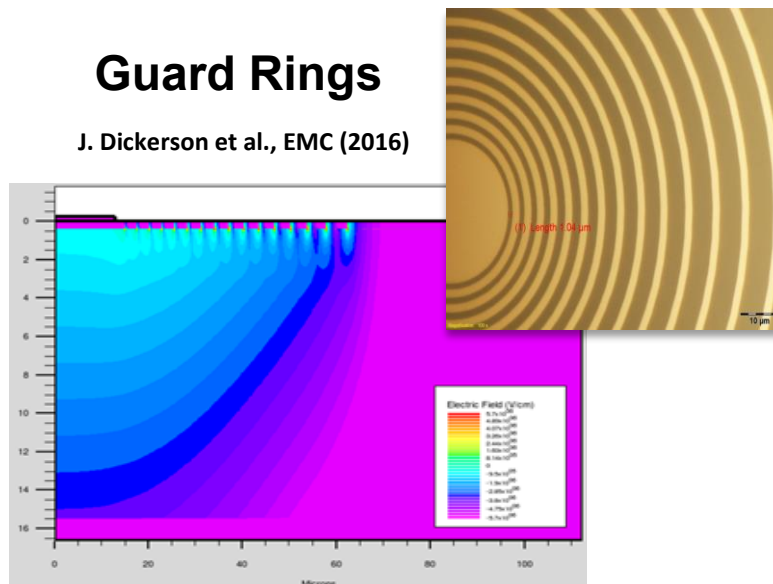
Reverse recovery measurements on vertical GaN diodes to determine carrier lifetime

- 100 V reversing pulses used with various forward currents
- Reverse-recovery time is invariant to forward bias, implying t_r is limited by capacitance
- Measured times provide an upper limit for hole lifetime – $\tau_h \approx 2$ ns



But premature breakdown will occur at the device surface, edge, etc. unless mitigations are taken to prevent this – edge termination

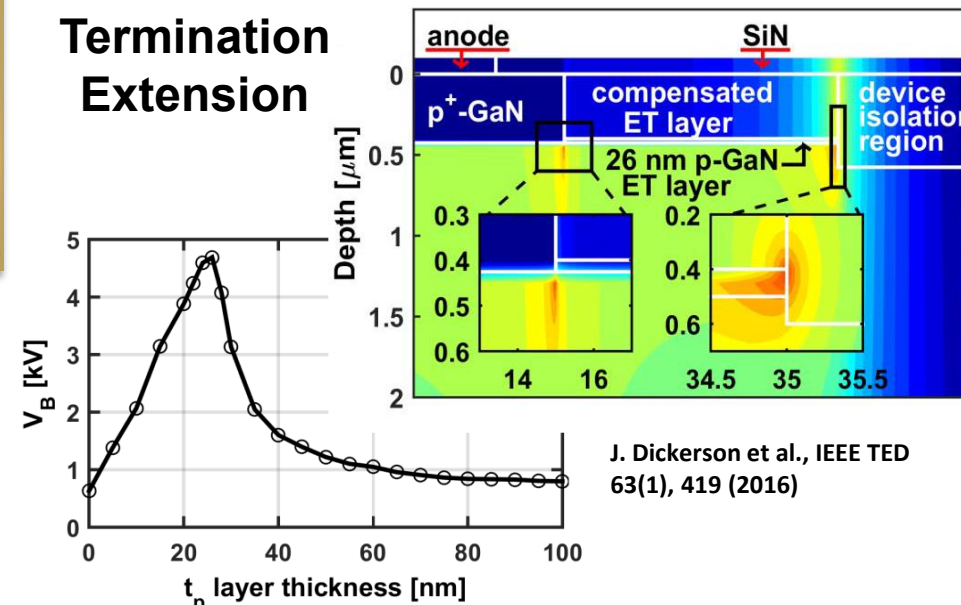
J. Dickerson et al., EMC (2016)



A. Binder et al., WiPDA (2019)

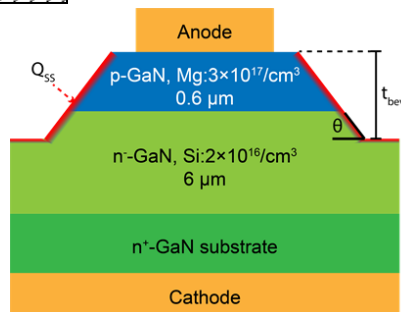
Various approaches to edge termination

Junction Termination Extension



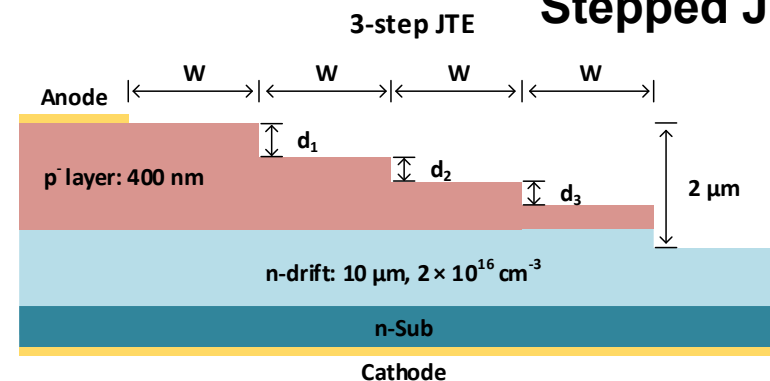
J. Dickerson et al., IEEE TED
63(1), 419 (2016)

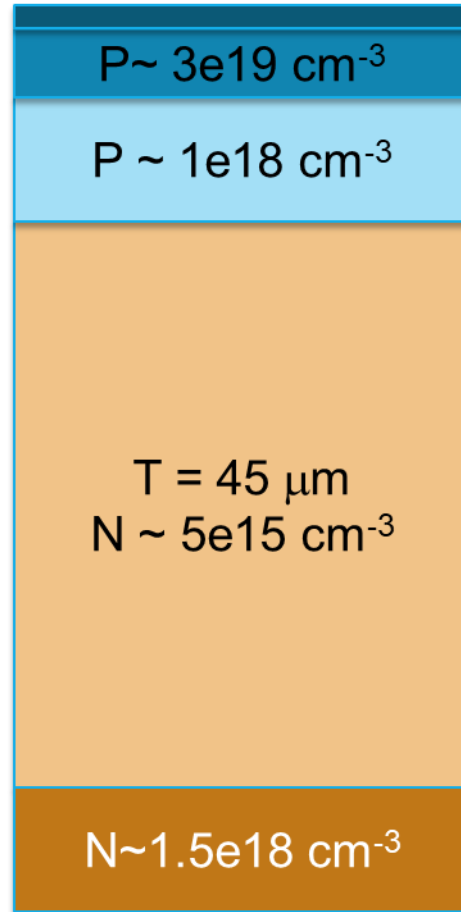
Bevel



K. Zeng

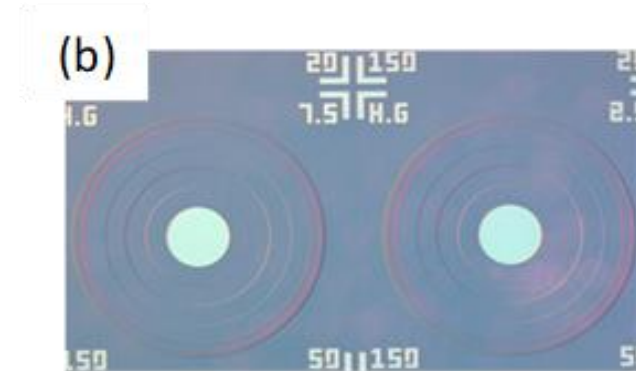
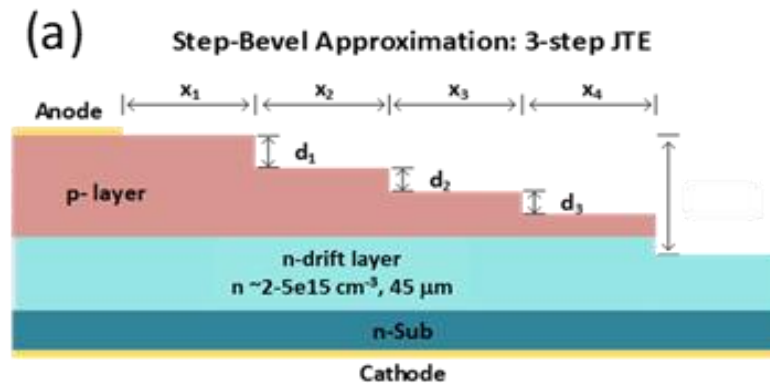
Stepped JTE





**C-V mapping confirmed highest reverse
breakdown voltage devices from regions
of wafer with drift region carrier density
 $\sim 2.2\text{-}3.0 \times 10^{15} \text{ cm}^{-3}$**

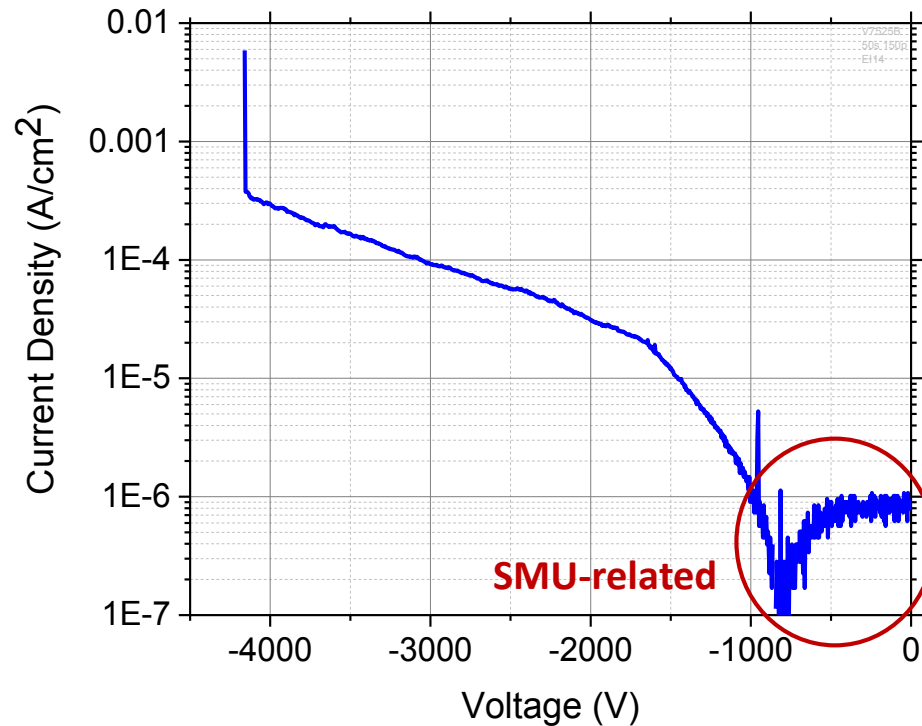
Edge termination: Multi-step ICP-etched JTE



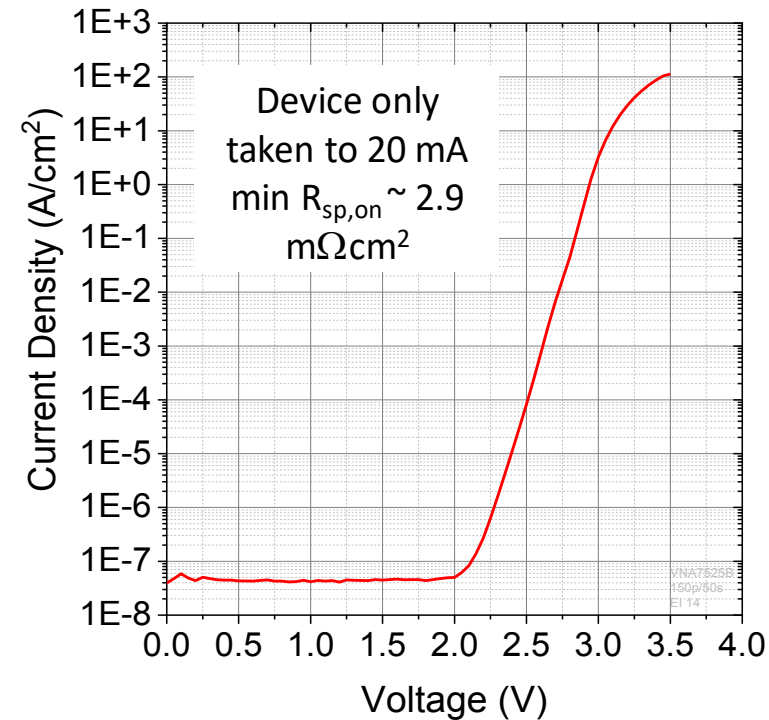
Performance of Medium-Voltage GaN Diodes



REVERSE I-V

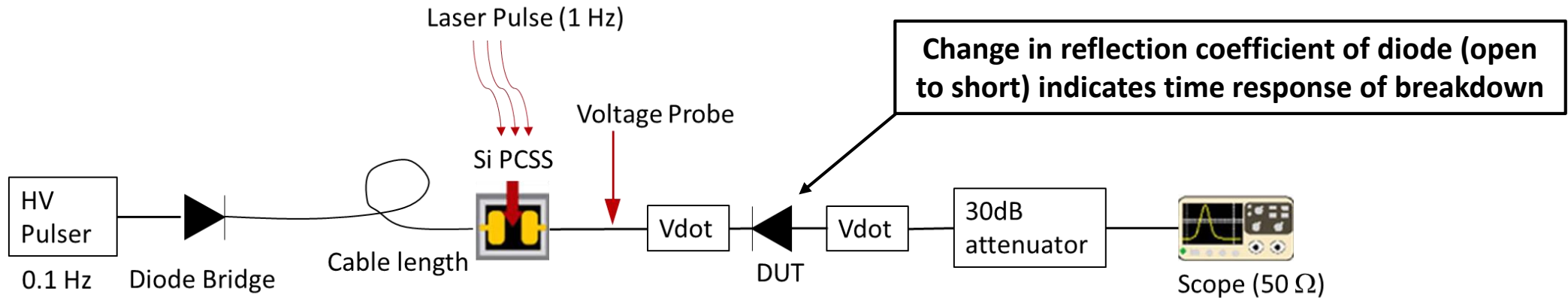


FORWARD I-V

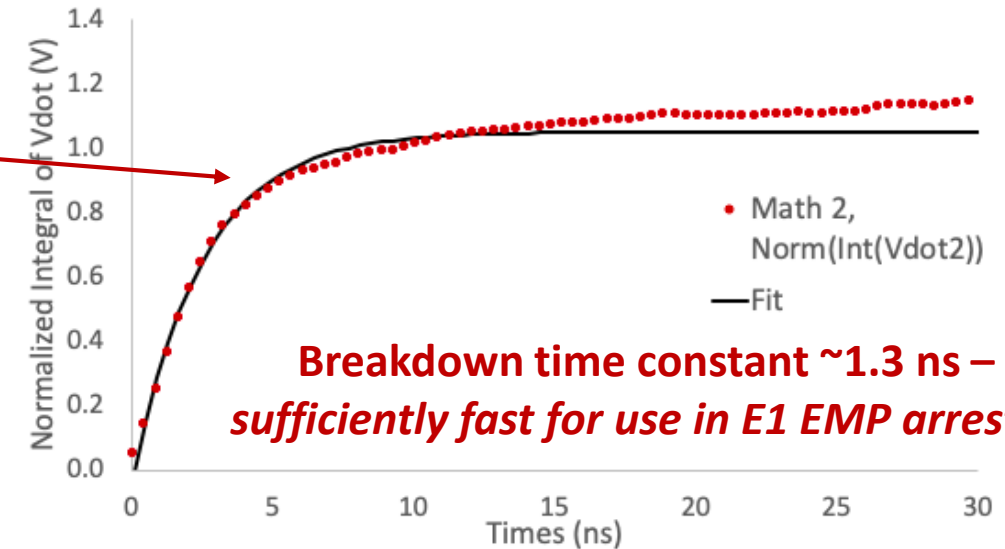
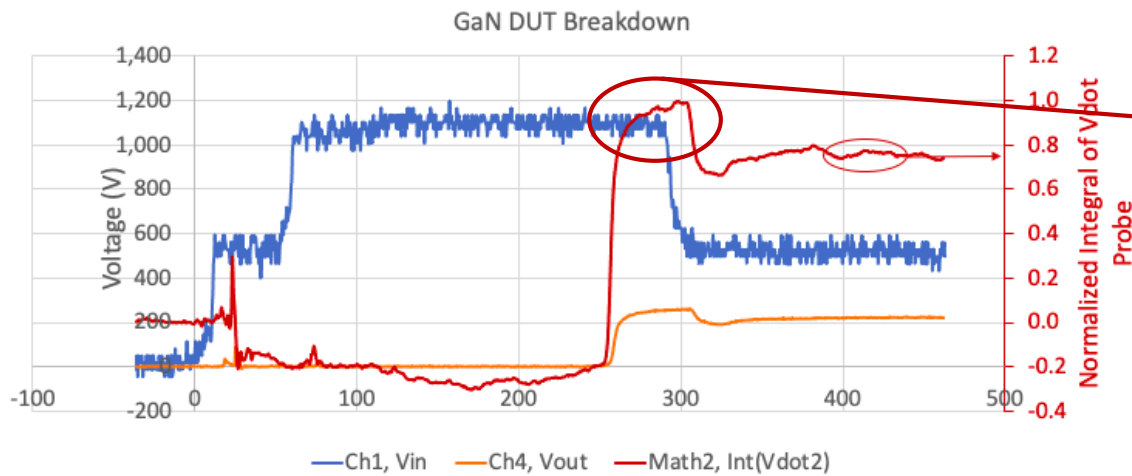


- Best devices > 4 kV; estimate ~70% V_B of ideal planar diode
- Less than 1 mA/cm² leakage @ 80% V_B target

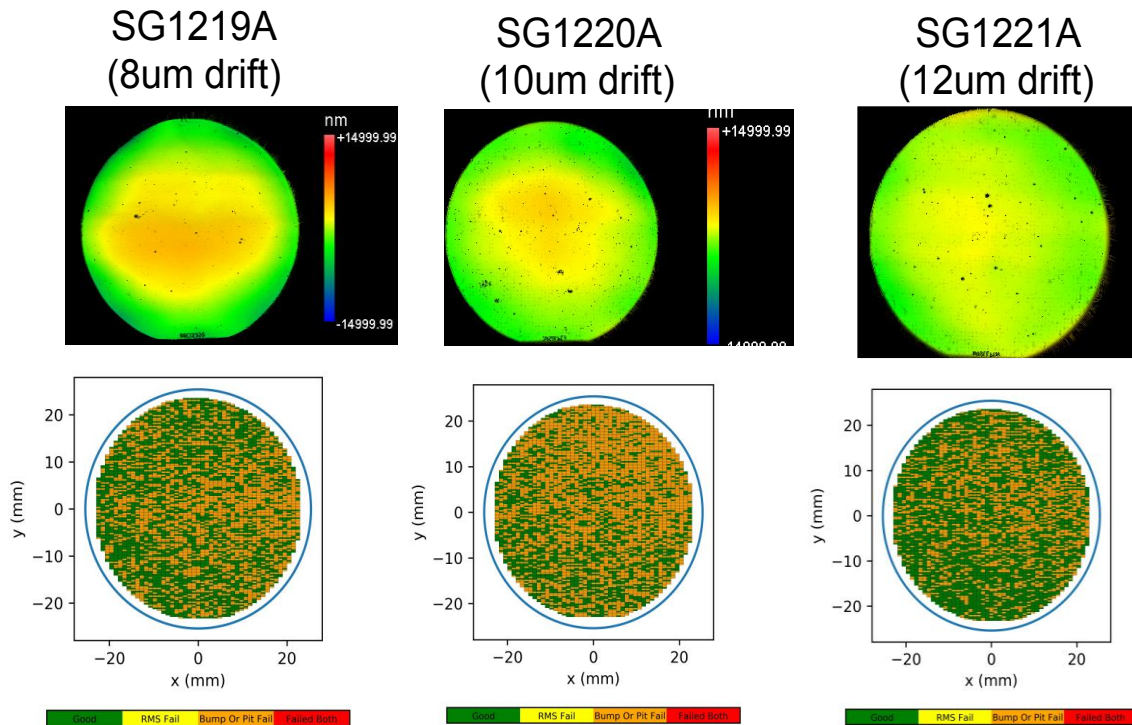
Time Response of GaN Avalanche Breakdown



Tested 1.2 kV vertical GaN diode

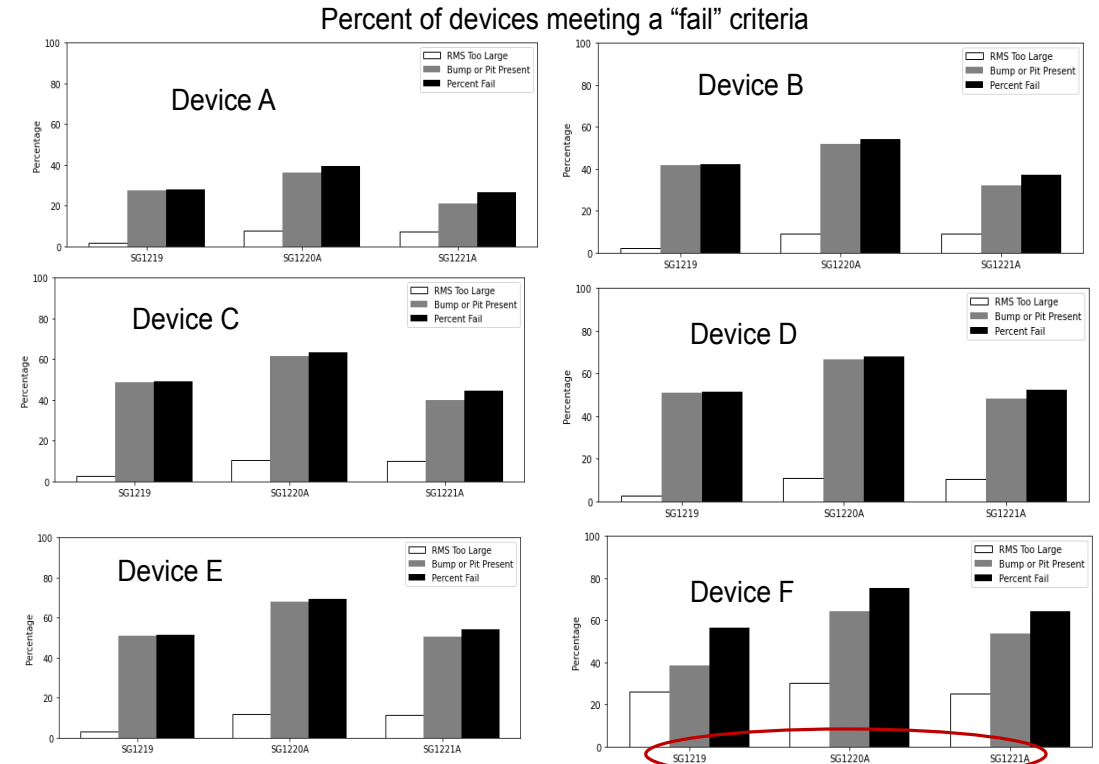


Vertical GaN Foundry Wafer Metrology

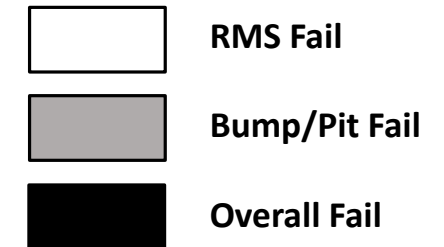


Good
RMS Fail
Bump/Pit Fail
Fail Both

- Evaluate yield based on particles/pits and RMS roughness
- No clear trend in RMS roughness with drift layer thickness
- Evaluating yield for device geometries A-F

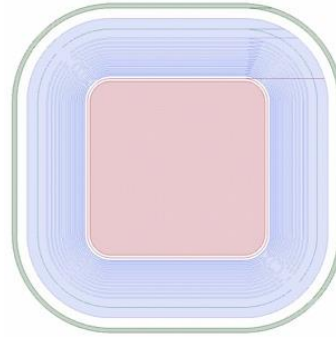
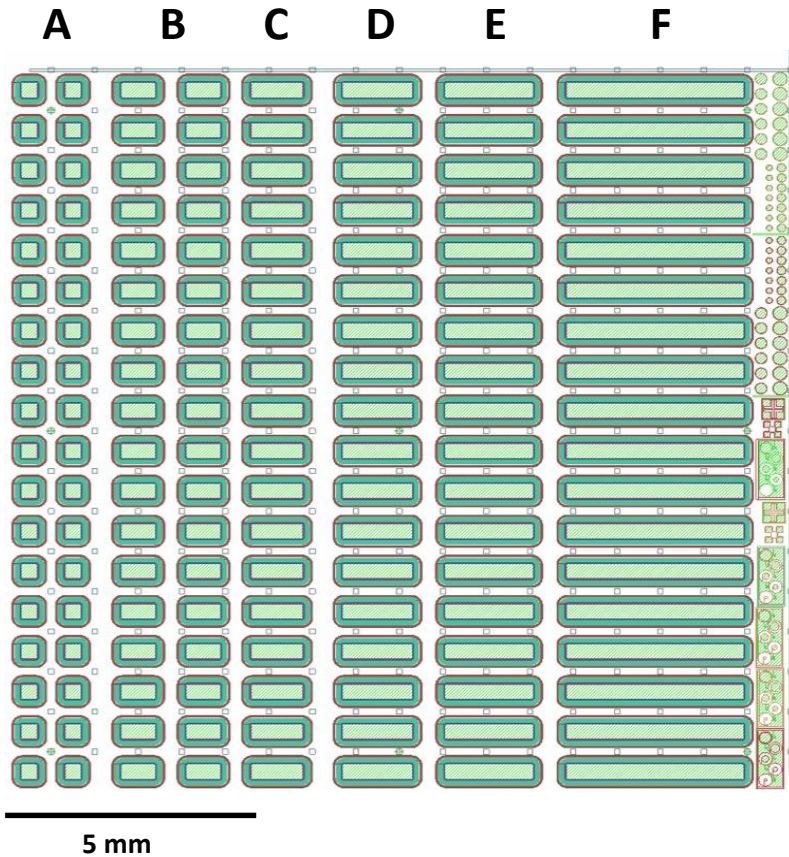


Geometry	Area (mm ²)	Devices (per 2" wafer)
A	0.105	280
B	0.215	280
C	0.325	150
D	0.430	150
E	0.535	150
F	1.05	140
Total		1150



T. Anderson, NRL

Foundry Mask Layout



Base cell:
0.35×0.35 mm² anode

Larger devices scaled only in x-direction to avoid crossing dot-cores (for now)

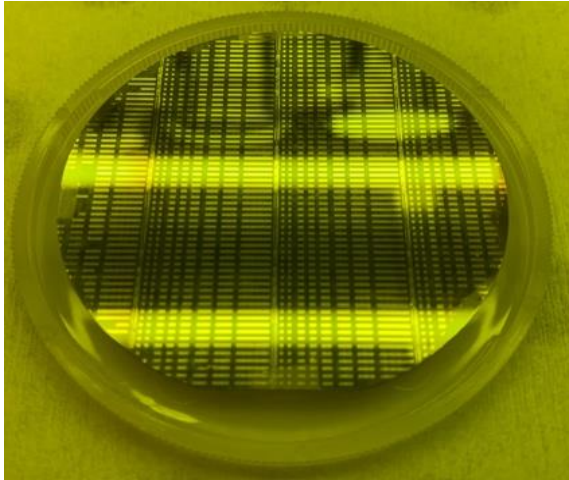
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Features:

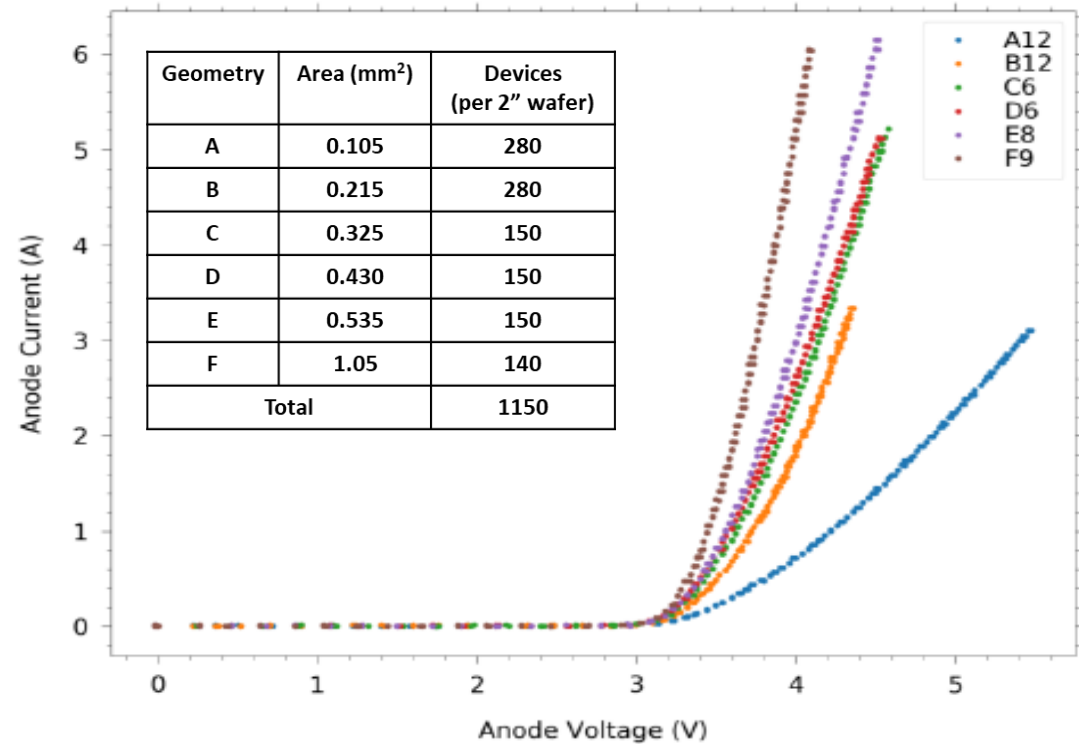
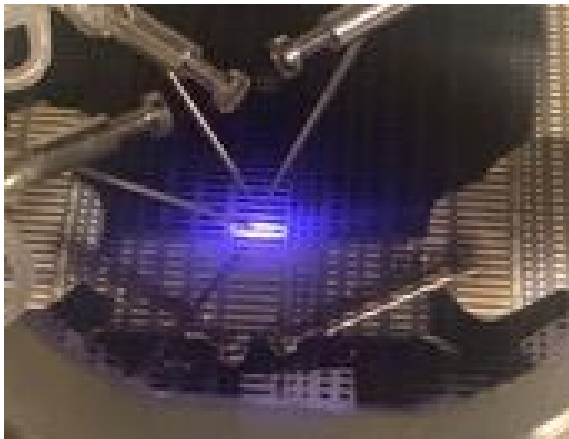
- Global alignment
- P-GaN ohmic CTLM
- P-GaN Hall
- Isolation test
- Termination test
- Small diameter circular diodes
- JTE and GR termination designs
- Passivation / overlay for packaging

Foundry Electrical Testing

Typical
foundry
wafer

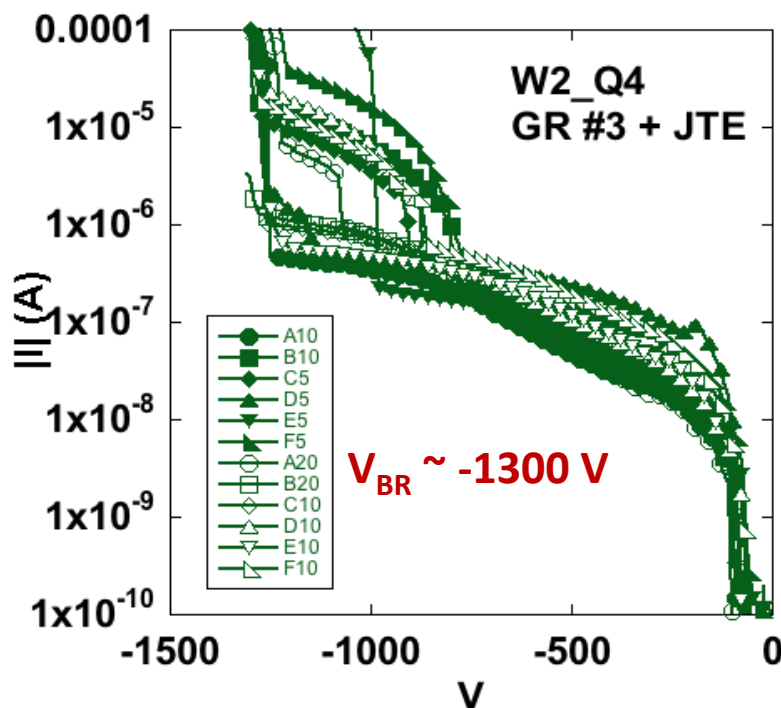


Wafer
under
test



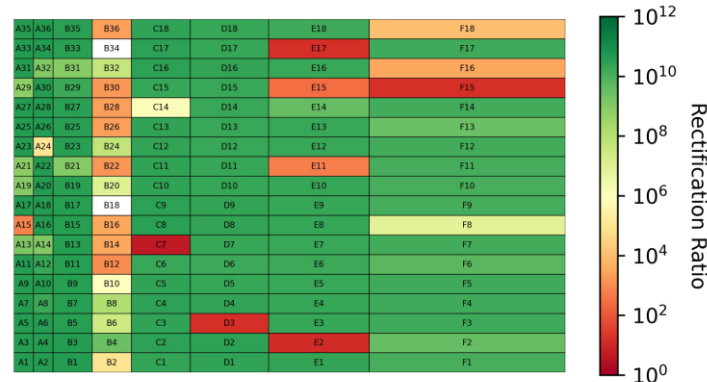
- Representative forward I-V curves for device types A-F
 - Largest devices achieve ~6 A forward current

Foundry Yield Analysis

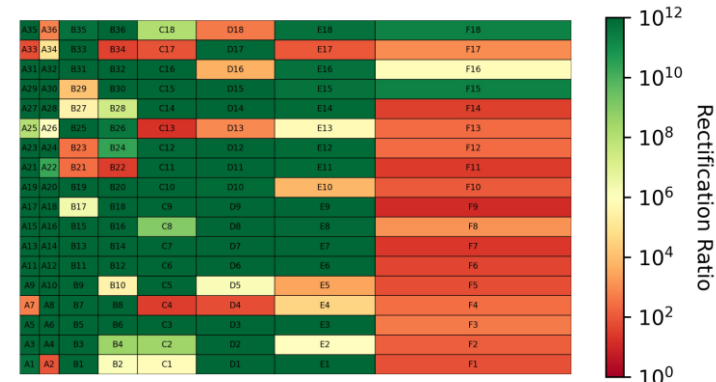


- Multiple devices achieve breakdown $>1.3 \text{ kV}$, which is $\sim 90\%$ of the parallel-plane value

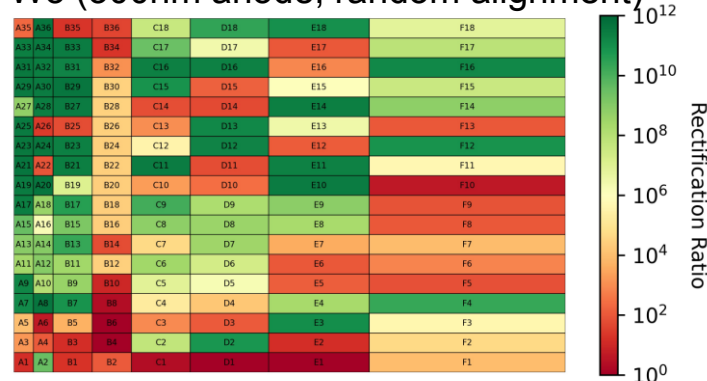
NL2-W1 (base structure, aligned to dot-core)



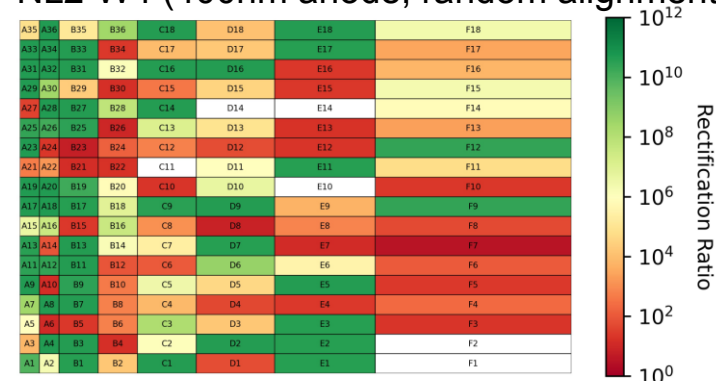
NL2-W2 (base structure, random alignment)



NL2-W3 (300nm anode, random alignment)



NL2-W4 (400nm anode, random alignment)



- ON/OFF ratio used for preliminary yield analysis – captures both devices that don't turn on OR don't turn off



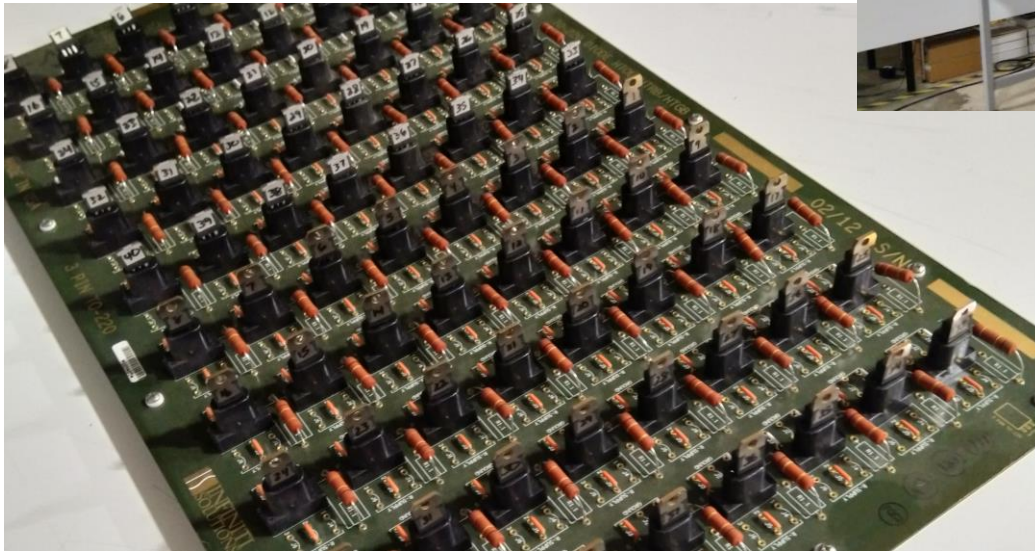
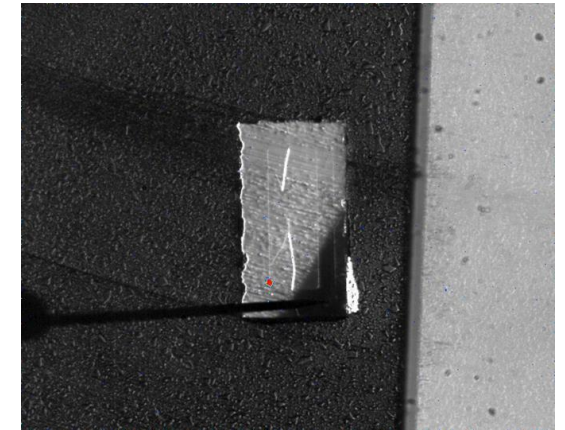
Reliability and Failure Analysis

- Extensive vertical GaN reliability and FA effort ongoing

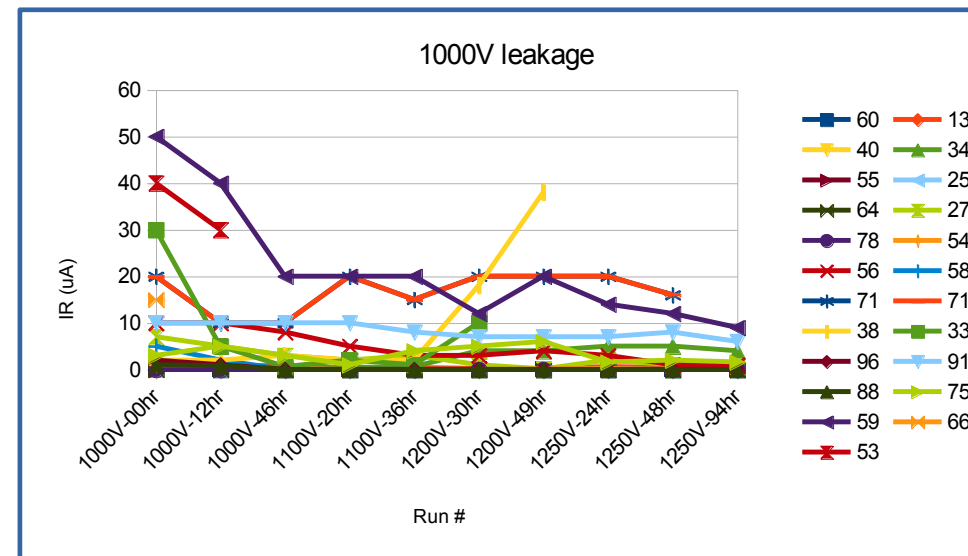
Reliability test ovens
and power supplies



Failure Analysis: Emission Microscopy (EMMI)



Reliability test board



High
Temperature
Reverse Bias
leakage
current data

O. Aktas, EDYNX

- Overview of WBG Power Electronics
- Medium-Voltage Vertical GaN Devices
 - PN Diodes
- **Vertical GaN Devices for Electric Vehicles**
 - **JBS Diodes and MOSFETs**

DOE Targets for Electric Vehicle Drivetrains

- The Department of Energy has partnered with several automotive and energy companies to create a tentative roadmap for improvements to electric vehicle drives.
- “... EETT has a 2025 power density research target of **33 kW/L for a 100 kW peak system**. While achieving this target will require transformational technology changes to current materials and processes, it is essential for enabling widespread electrification across all light-duty vehicle platforms.”
- 33 kW/L target is for motor plus power electronic drive; PE target is 100 kW/L for 100 kW system
- Reliability and cost targets are also specified

For more information about U.S. DRIVE, please see the U.S. DRIVE Partnership Plan at www.vehicles.energy.gov/about/partnerships/usdrive.html



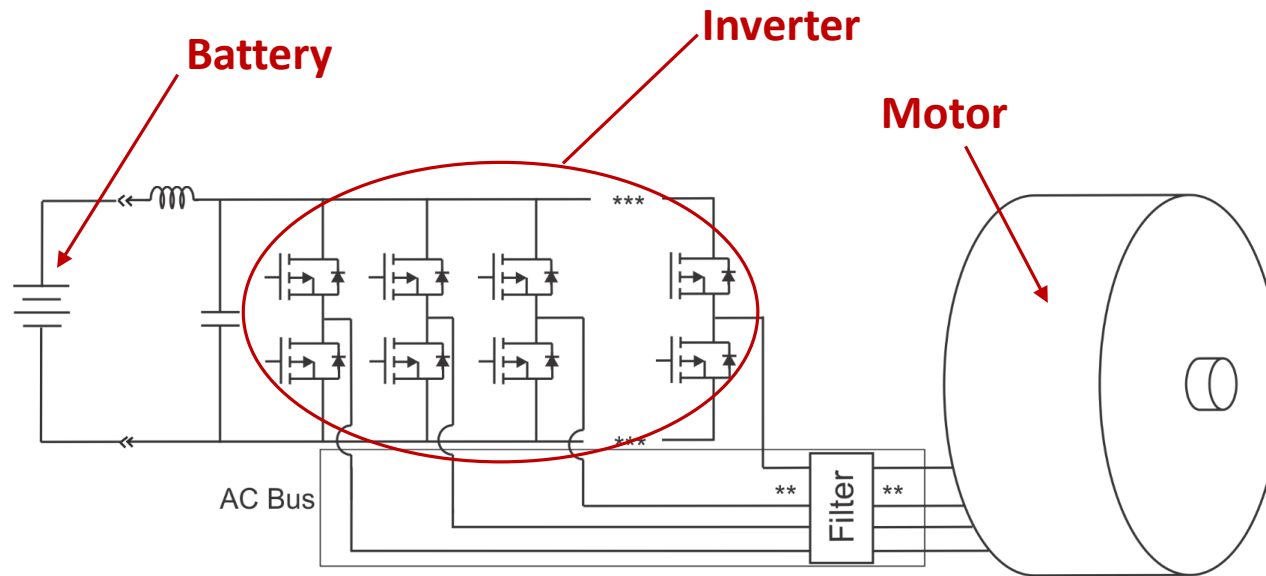
Electrical and Electronics Technical Team Roadmap

October 2017

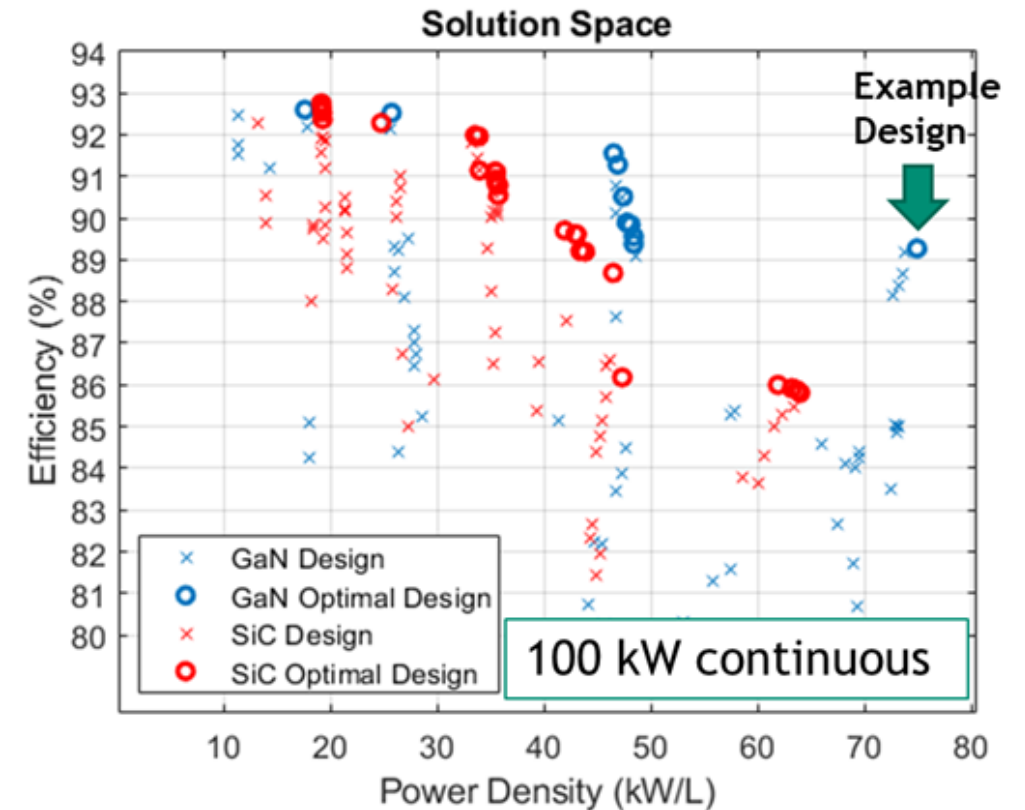


Advantages of Vertical GaN for Electric Vehicles

Electric Drivetrain Schematic



- Inverter and optional boost converter require switch-diode pairs (typical for switch-mode power conversion circuits)
- MOSFET and JBS diode are likely good choices (JBS diode combines best properties of Schottky and PN diodes)



- System-level genetic optimization indicates that vertical GaN diodes may out-perform SiC in terms of efficiency and power density

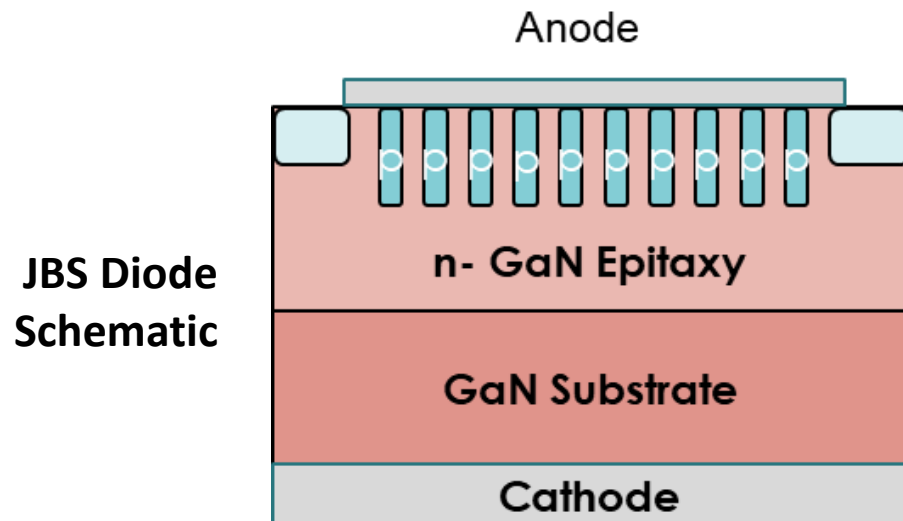
Vertical GaN JBS Diode Development

Fabrication of GaN JBS diodes:

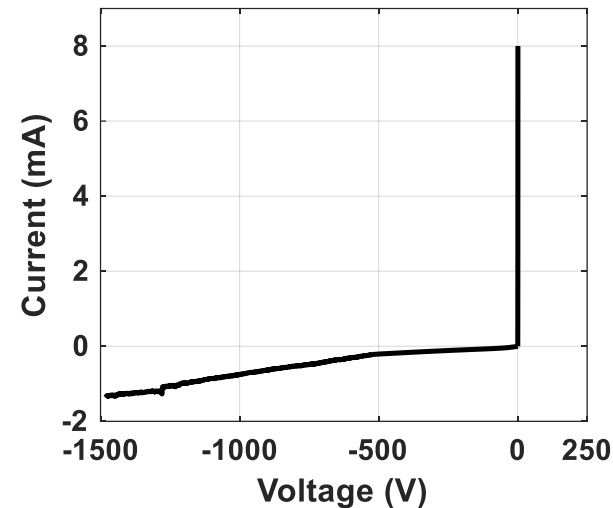
- Etched-and-regrown JBS diode demonstrated
- 1500 V reverse holdoff voltage

Next Steps:

- Exploring regrowth surface pre-treatment strategies to reduce current leakage
- Added JTE to aid in field management and improve reverse breakdown

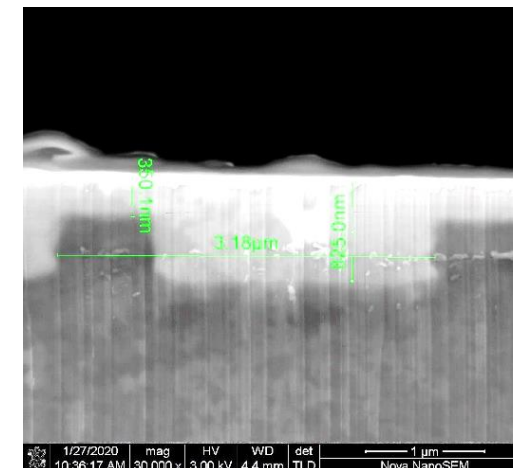


IV curve for gen 1 GaN JBS diode

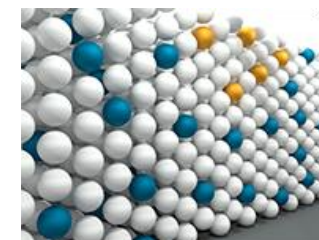
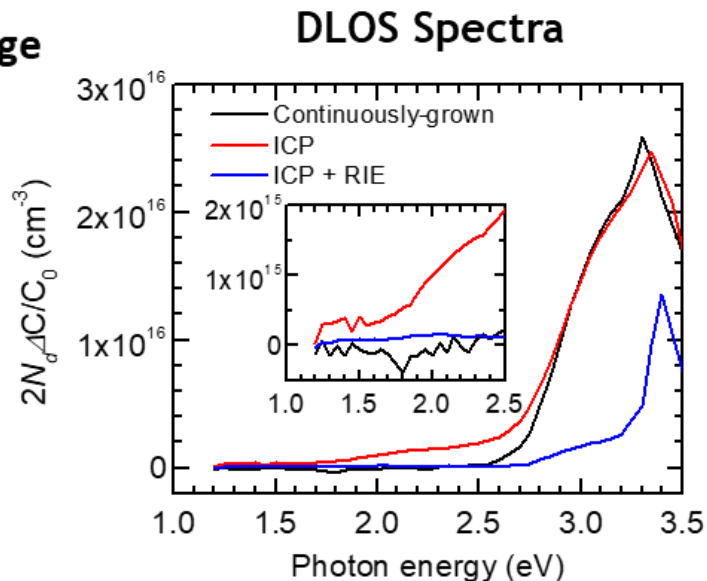
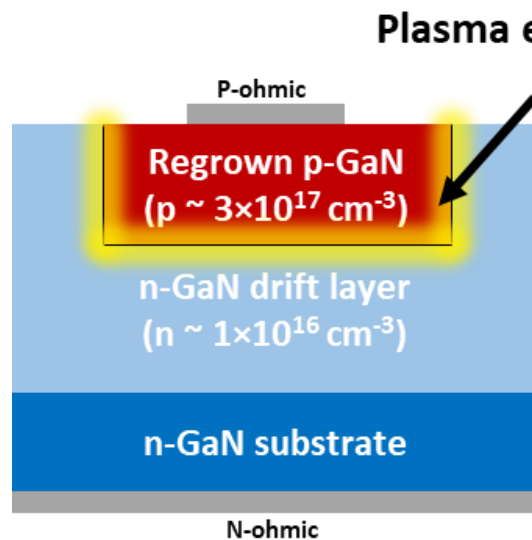


- Low turn-on voltage (consistent with Schottky)
- Low leakage current (consistent with PN junction)
- Confirms JBS operation

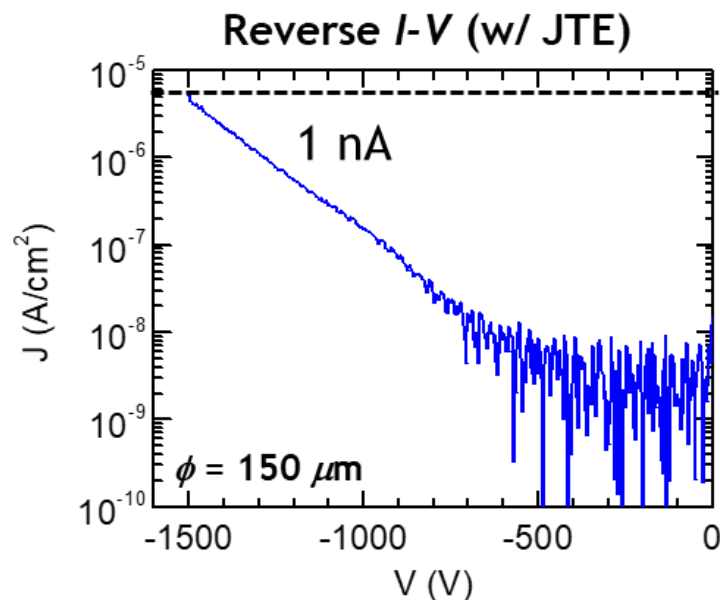
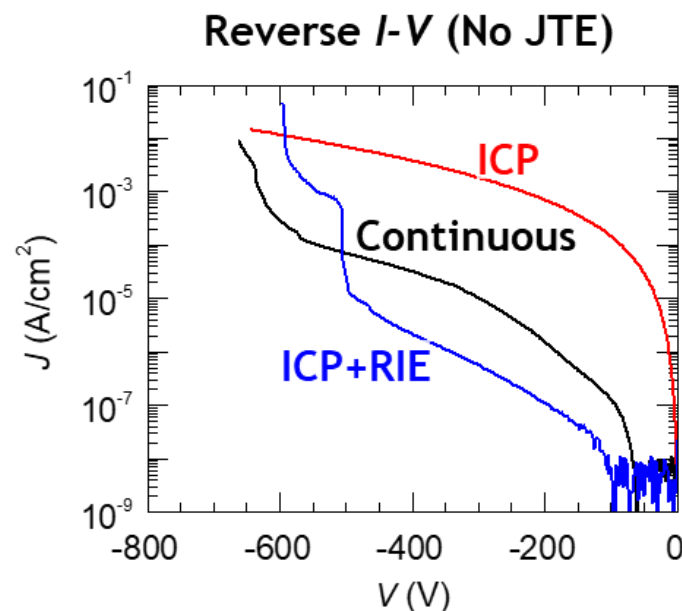
Cross-Sectional SEM of Regrown PN Junction



Etch and Regrowth Needed for JBS Diodes



PNDIODES



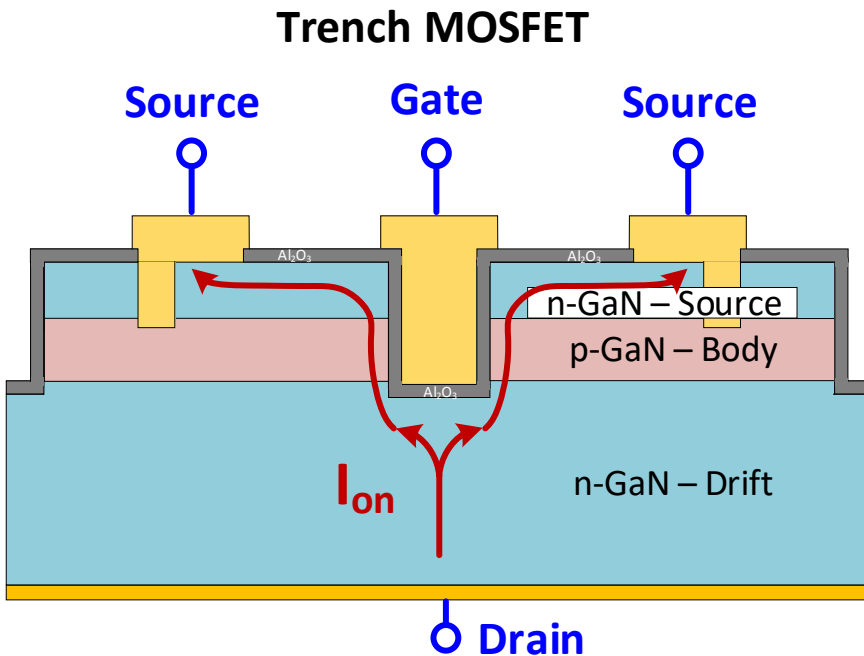
- Correlated $E_c - 1.9 \text{ eV}$ deep level with plasma damage and leakage
- Removed plasma damage with post-ICP RIE step
- Achieved etched-and-regrown diode $> 1.5 \text{ kV}$ and $1.4 \text{ m}\Omega\cdot\text{cm}^2$

Vertical GaN MOSFET Development



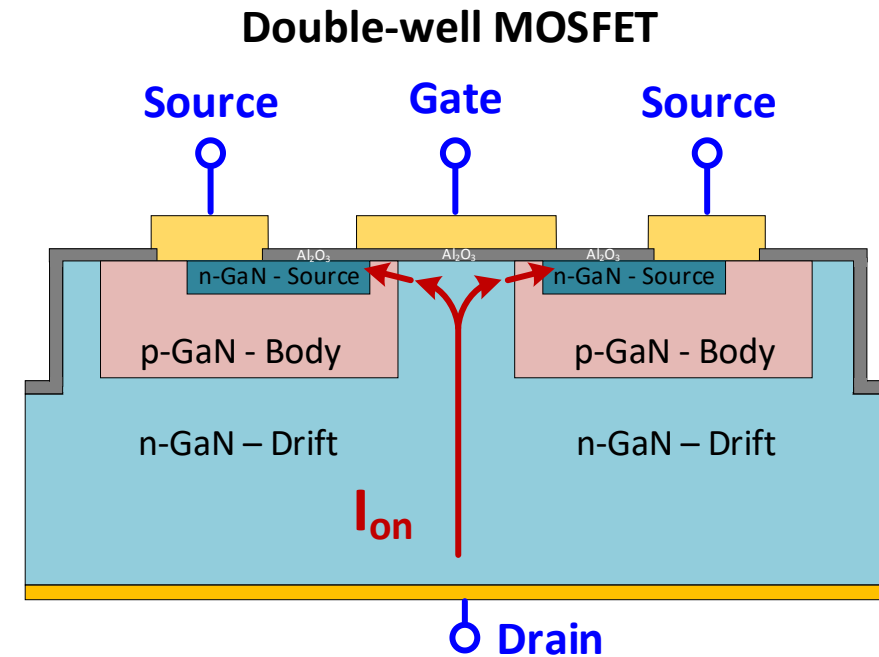
Trench MOSFET key features:

- Selective-area doping not needed for body and source
- Gate on vertical etched GaN sidewall
- High fields at bottom trench corner

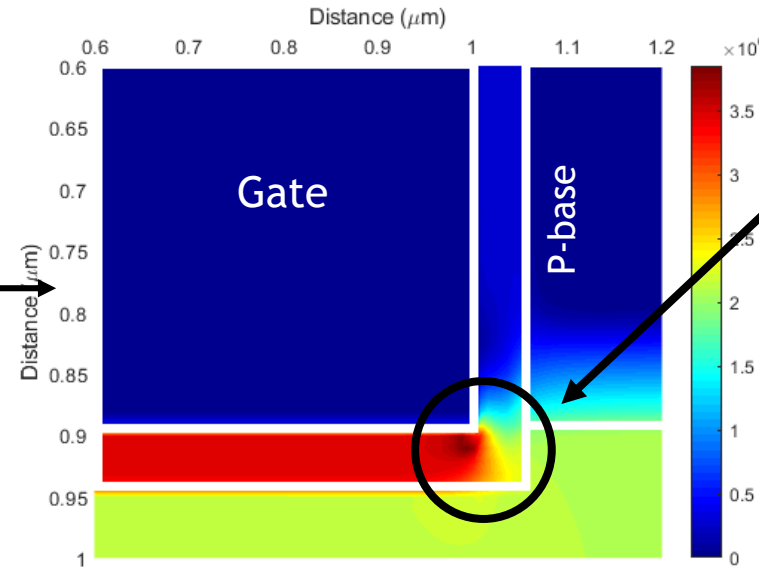
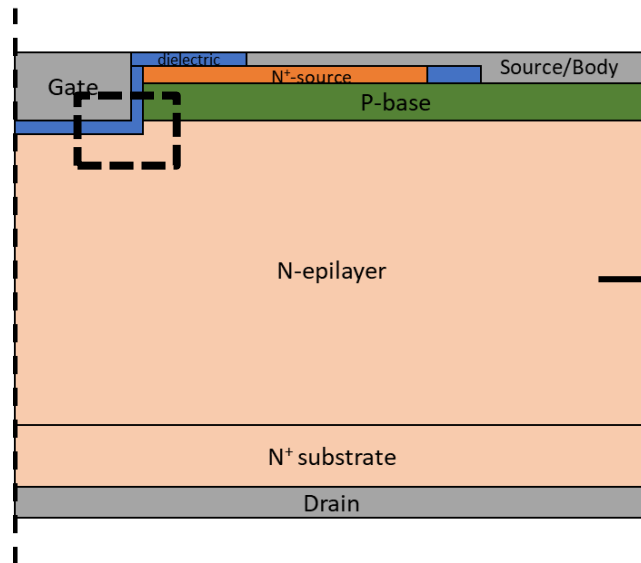


Double-well MOSFET key features:

- Selective-area doping required for body and source
- Gate on planar top surface
- JFET region engineering critical

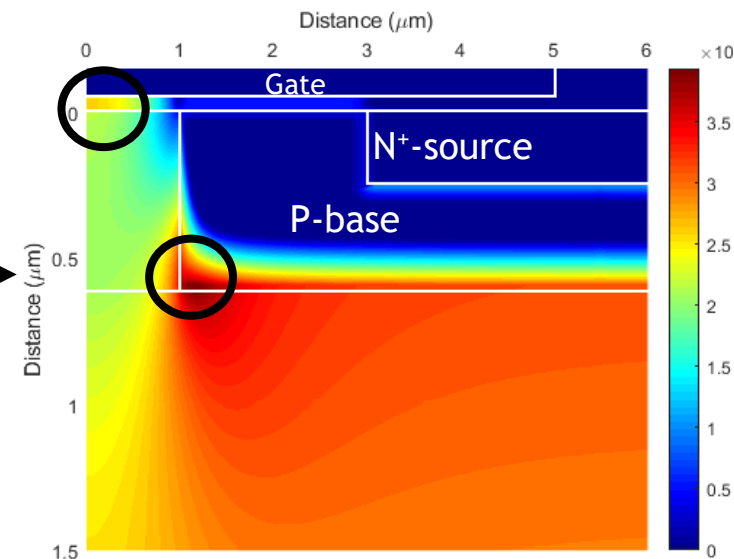
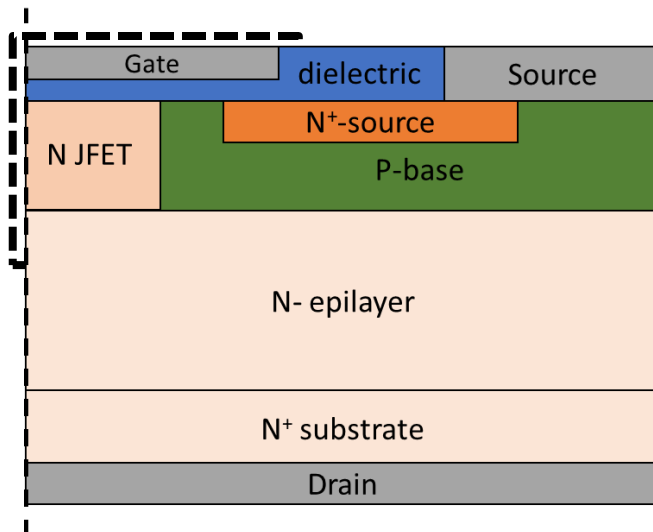


TCAD Simulation of T-MOSFET and D-MOSFET



Field crowding at the corner of the gate elevates electric field in dielectric

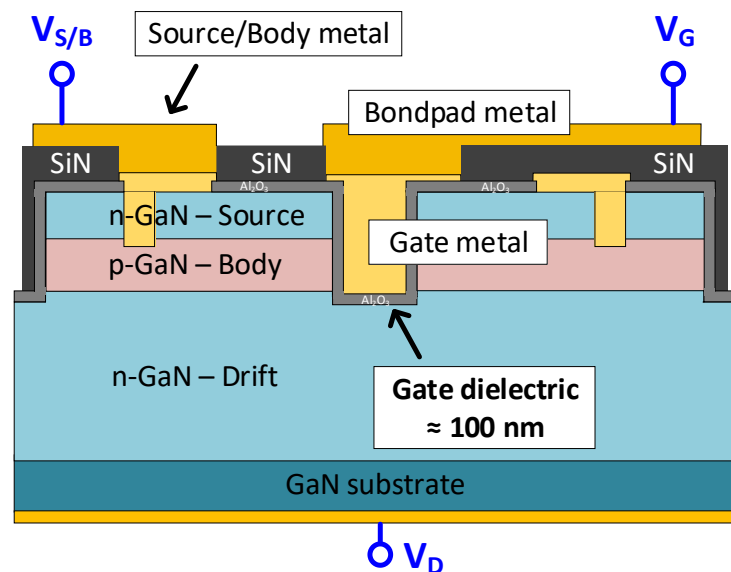
Electric field taken at $V_g=0$ and $V_{DS}=1200$ V



- Large electric field occurs in GaN at corner of JFET region
- Largest dielectric E-field occurs under center of gate

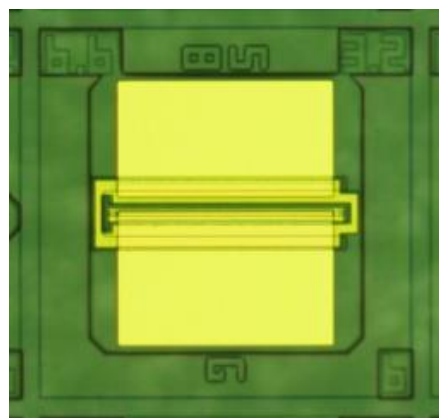
Initial Trench MOSFET Electrical Data

T-MOSFET Diagram

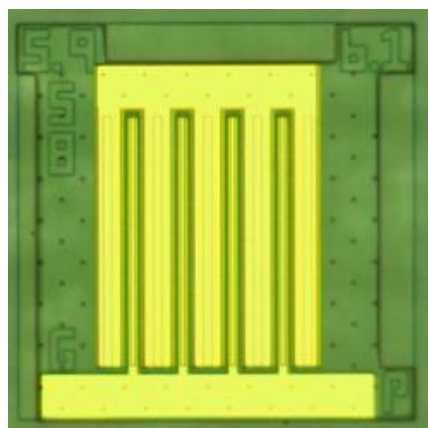


- T-MOSFETs demonstrated
- Devices have a good on/off ratio, $\sim 10^8$
- Positive threshold voltage: ~ 8 V
- Current density ~ 400 mA/mm achieved
 - Single-finger and four-finger devices fabricated

Single-finger



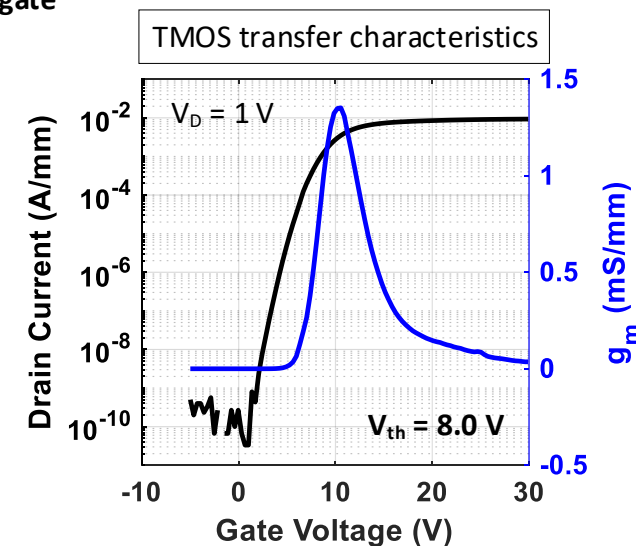
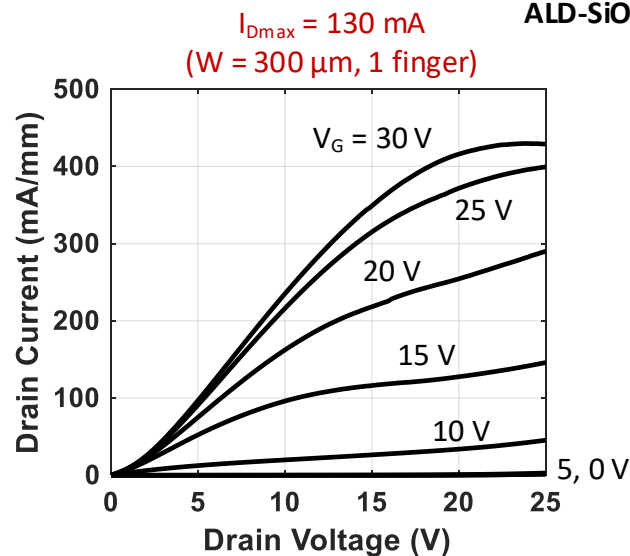
Four-finger




Lot 5: Single Finger MOSFET

ALD-SiO₂ gate

VNA7682C-D: 6.5-4.4



- 
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Questions?
Bob Kaplar: rjkapla@sandia.gov